



# Vacuum System Development of HEPS

**Yongsheng Ma** On behalf of vacuum system

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Xiaohua Peng, Tao Huang, Pulong Tian

Pengcheng Wang, Jiaming Liu, Xiaoyang Sun, Bangle zhu

2023-2-14



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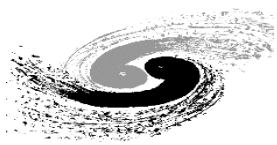
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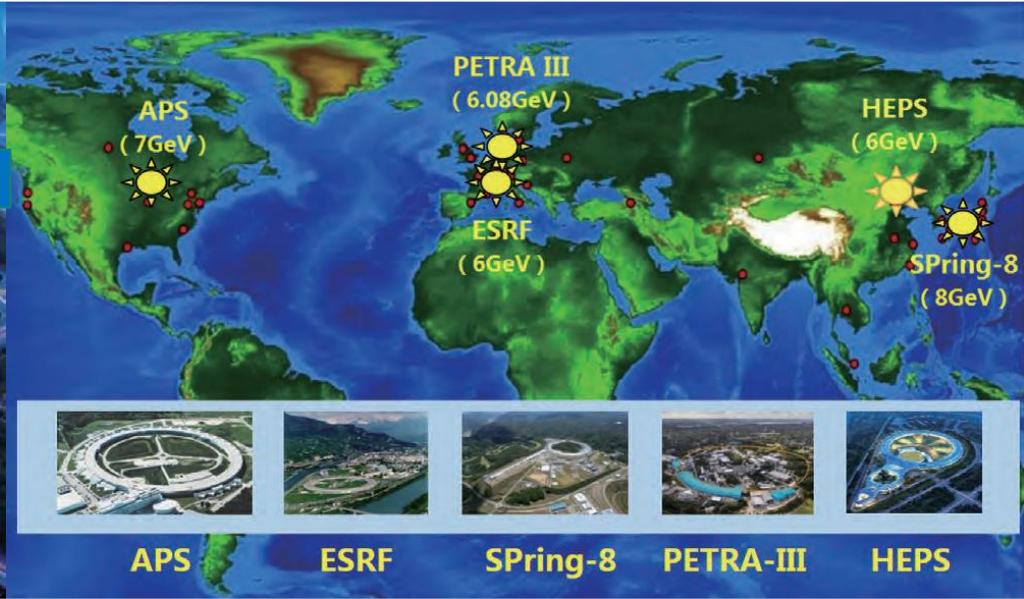
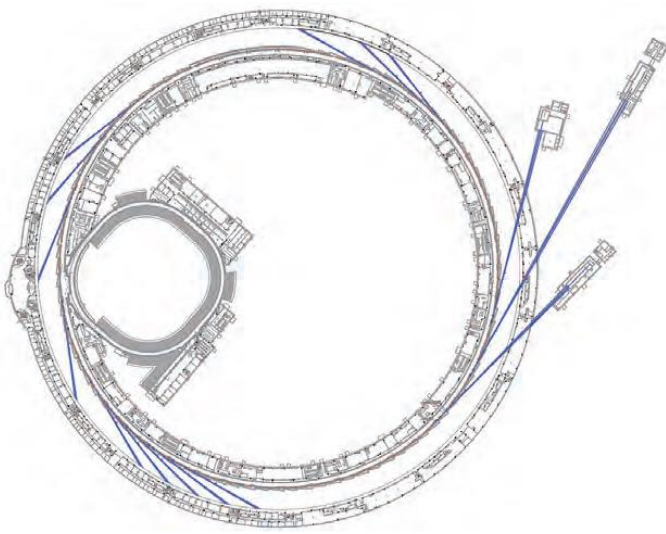
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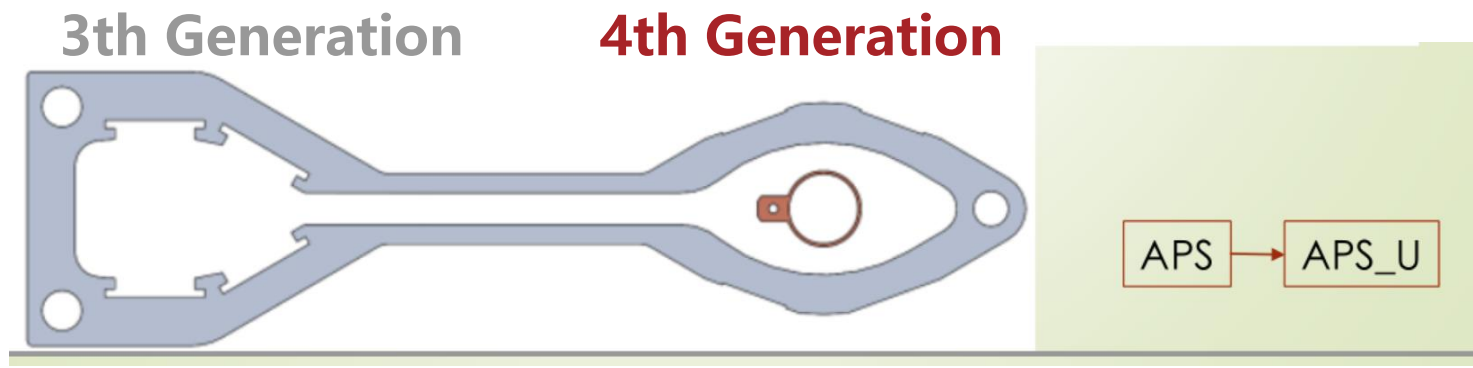
# 1 Preview of HEPS vacuum system

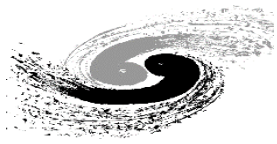
Haiyi Dong

## ◆ High Energy Photon Source



## ◆ Storage ring vacuum chamber changes to much smaller from 3th Generation To 4th Generation



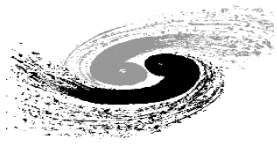


# 1 Preview of HEPS vacuum system

Haiyi Dong

|              | Energy           | Material                       | Cross Section/mm                         | Length /m | Dynamic pressure /Torr                               |
|--------------|------------------|--------------------------------|--|-----------|--|
| LINAC        | 500 MeV          | Stainless steel, copper        | Φ30                                      | 49        | Acc $<2 \times 10^{-7}$<br>E-gun $<2 \times 10^{-8}$ |
| Booster      | 500 MeV to 6 GeV | Stainless steel                | 36×30 (H×V) ellipse / thickness of 0.7mm | 454       | $<3 \times 10^{-8}$                                  |
| Storage Ring | <b>6 GeV</b>     | Extruded copper, S.S, NEG film | φ22/thickness of 1mm                     | 1360.4    | $<3 \times 10^{-9}$                                  |
| LTB          | 500 MeV          | Stainless steel                | φ30/thickness of 1mm                     | 25        | $<1 \times 10^{-7}$                                  |
| BTS(STB)     | 6 GeV            | Stainless steel                | φ26/thickness of 1mm                     | 105       | $<1 \times 10^{-7}$                                  |

| Facility           | C(m).                        | E(GeV)/I(A)<br>Ex(pm.rad)         | Mag. Bore(mm) | Chamber Material                        | Baking Method  |
|--------------------|------------------------------|-----------------------------------|---------------|---|----------------|
| MAX-IV<br>(Sweden) | 528<br>(20cell-7BA)          | 3/0.5<br>330                      | 25            | OFS Cu<br>(100% NEG Coating)            | Ex-situ        |
| SIRIUS (Brazil)    | 518.4<br>(20cell-5BA)        | 3/0.5<br>250                      | 28            | OFS Cu<br>(100% NEG Coating)            | In-situ        |
| EBS (France)       | 844<br>(32cell-7BA)          | 6/0.2<br>135                      | 26            | SST/Al<br>(Partial NEG Coating)         | In-situ        |
| APS_U (USA)        | 1100<br>(40cell-7BA)         | 6/0.2<br>60                       | 26            | OFS Cu/Al<br>(Partial NEG Coating)      | Ex-situ        |
| <b>HEPS</b>        | <b>1346<br/>(48cell-7BA)</b> | <b>6/0.2<br/>35<sup>[1]</sup></b> | <b>26</b>     | <b>CrZrCu<br/>(Partial NEG coating)</b> | <b>In-situ</b> |



# 1 SR power and gas load

To estimate the desorption rate, we follow the approach of Grobner et al. [1983]. The effective gas load due to photodesorption is found to be

$$Q_{gas} = 24.2EI\eta \text{ [Torr}\cdot\text{L/s]},$$

Where  $E$  is the beam energy in GeV,  $I$  the beam current in A, and  $\eta$  the photodesorption coefficient in molecules/photon. The photodesorption coefficient  $\eta$  is a property of the chamber that depends on several factors:

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|              | <b>E</b> | <b>I</b> | <b><math>\rho</math></b> | <b>Psr</b> | <b>PL</b> | <b>PSD</b>       | <b><math>q_{th}</math></b> | <b><math>Q_{gas}</math></b> | <b><math>Q_{LSR}</math></b> |
|--------------|----------|----------|--------------------------|------------|-----------|------------------|----------------------------|-----------------------------|-----------------------------|
|              | Gev      | A        | m                        | MW         | W/m       | molecules/photon | Torr·L/s·cm <sup>2</sup>   | Torr·L/s                    | Torr·L/s·m                  |
| Booster      | 6        | 0.015    | 28.52                    | 60.32      | 336.8     | 2.00E-06         | 1.0E-11                    | 4.36E-06                    | 2.43E-08                    |
| Storage ring | 6        | 0.2      | 53                       | 432.82     | 1300.4    | 2.00E-06         | 2.5E-12                    | 5.81E-05                    | 1.74E-07                    |

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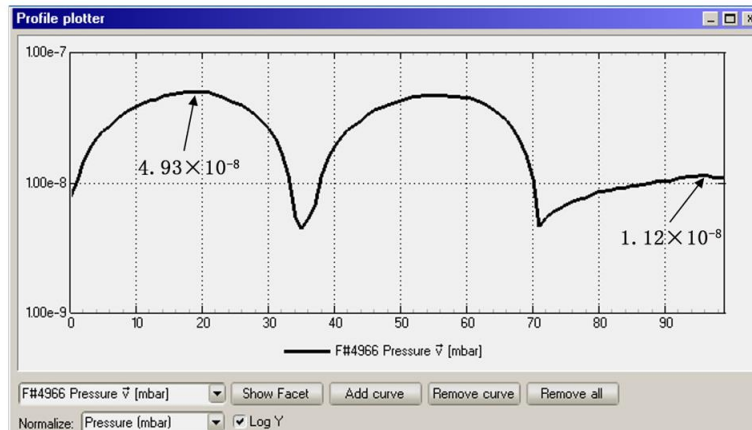


# 2 Layout of Linac vacuum system

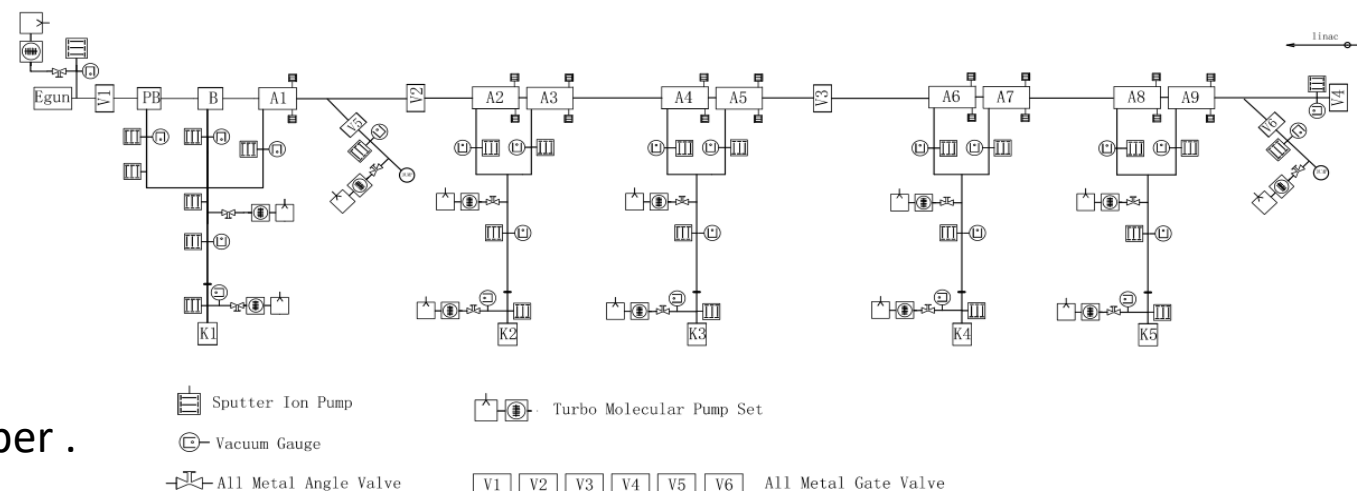
Hong Song

- ◆ The Linac vacuum system with a length of 49m is divided into 6 sections. it consists of electron gun, bunching system, accelerating structures and Analyzer Magnet sections.
- ◆ Sputter ion pumps: 45; Vacuum gauges: 25; Gate valves: 6

| Section                | Static pressure /Torr | Dynamic pressure /Torr |
|------------------------|-----------------------|------------------------|
| E-gun                  | $<1 \times 10^{-9}$   | $<2 \times 10^{-8}$    |
| Buncher                | $<5 \times 10^{-8}$   | $<2 \times 10^{-7}$    |
| Accelerating structure | $<5 \times 10^{-8}$   | $<2 \times 10^{-7}$    |
| AM                     | $<5 \times 10^{-8}$   | $<5 \times 10^{-7}$    |
| Waveguide              | $<5 \times 10^{-8}$   | $<5 \times 10^{-7}$    |



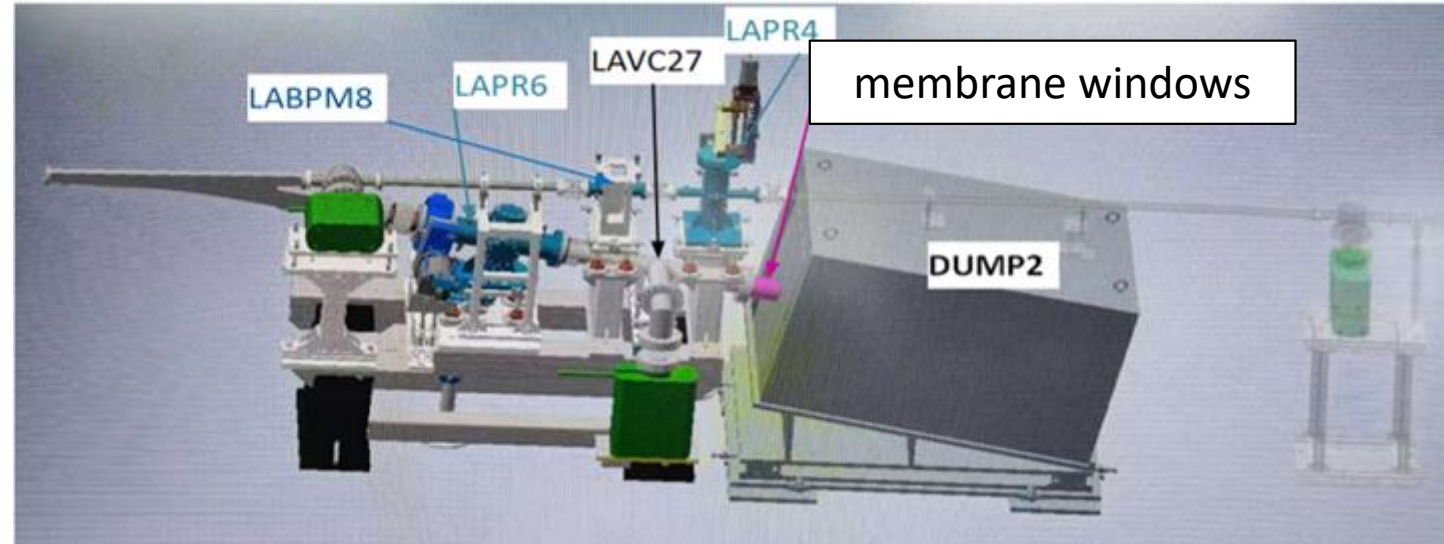
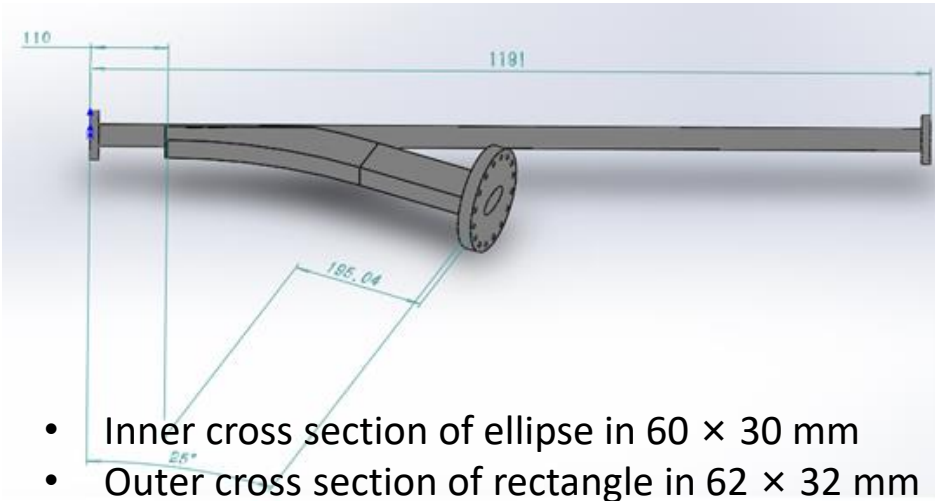
Most of the components are made of oxygen-free copper .  
The thermal outgassing rate is  $1 \times 10^{-11}$  Torr·l/s·cm<sup>2</sup>.





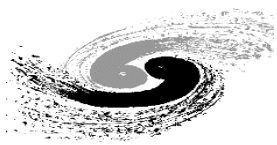
# Dump chambers and membrane windows for Linac

- ◆ The elliptical Ti thin membrane window of  $170 \times 10$  mm with a thickness of 0.1 mm was welded on the s. s. plate with a diameter of 183 mm and a thickness of 5mm.



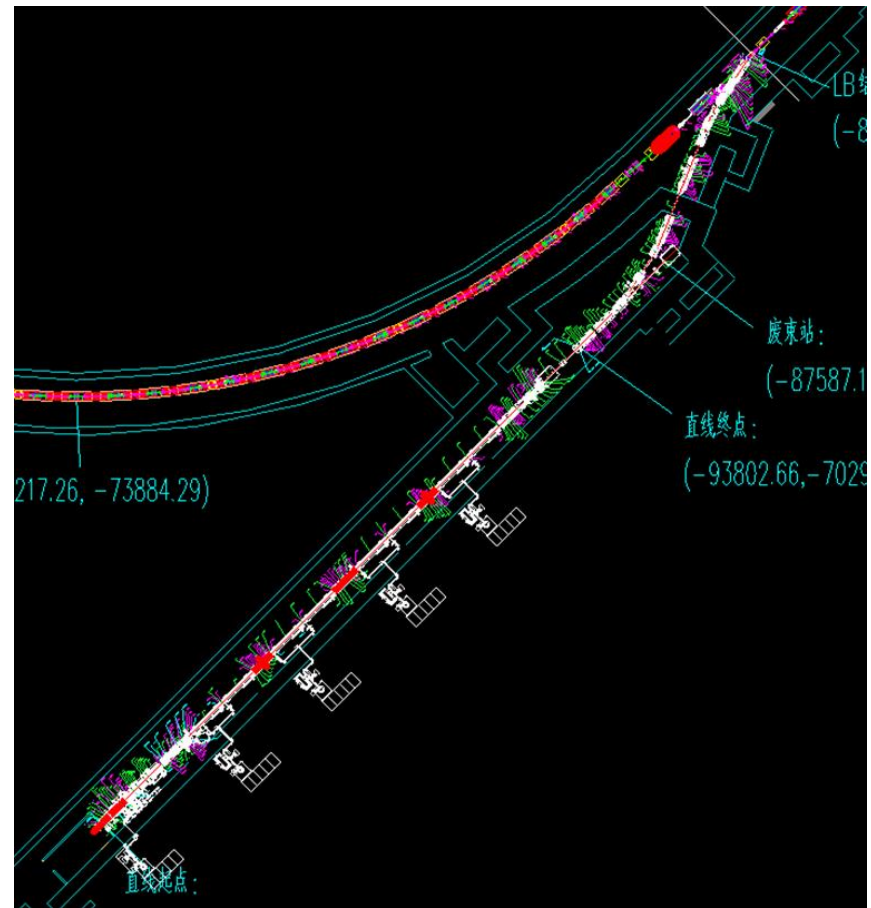
## ◆ Membrane windows

- The thickness of Ti window is 0.1mm
- Deformation test under vacuum: elliptical window is 0.4mm, circle window is 2.3mm;
- ultimate vacuum  $< 5 \times 10^{-8}$  Pa.

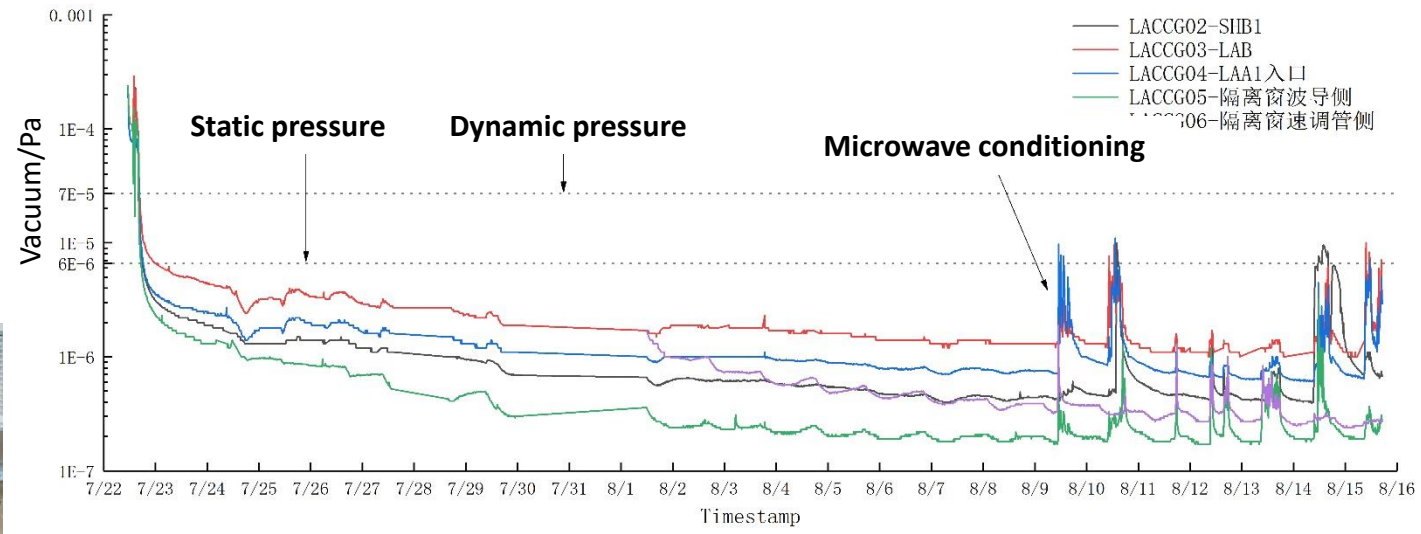


# 2 Status of Linac

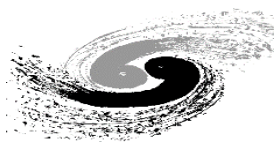
- ◆ The installation of all devices of Linac has been finished by July 2022,
- ◆ The static pressure reached its design value .



K1 section vacuum curve vs date

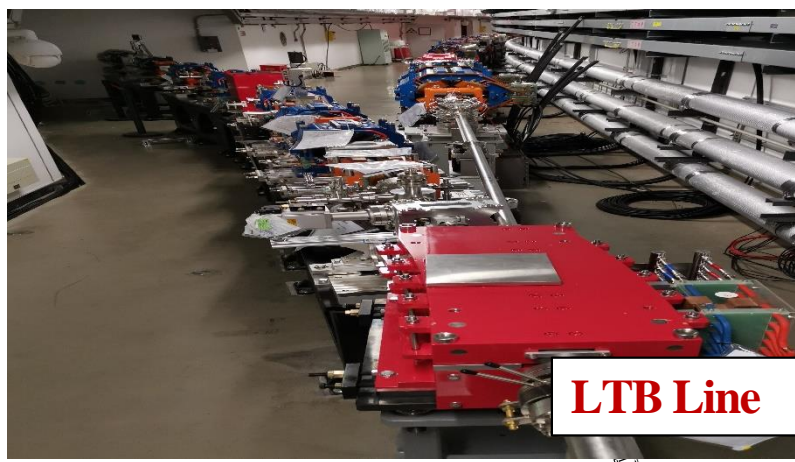






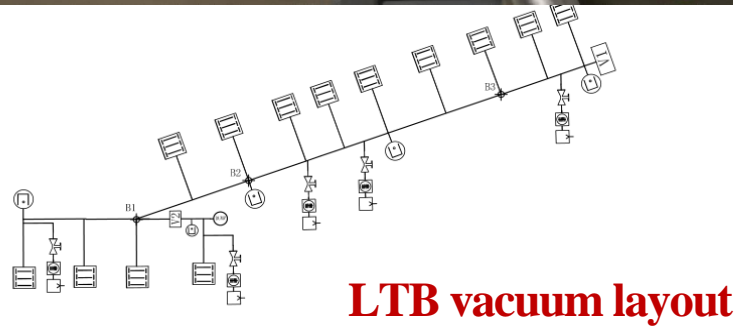
# 2 Introduction of transportation lines

- There are three beam transport lines. One is used to transfer 500MeV electrons from linac to the booster (LTB), the other two lines are used to transfer 6GeV electrons from booster to storage ring (BTS), and storage ring to booster (STB).
- Thermal outgassing rate is  $1 \times 10^{-10}$  Torr-l/(s·cm<sup>2</sup>). The dynamic vacuum pressure <  $1 \times 10^{-7}$  Torr.



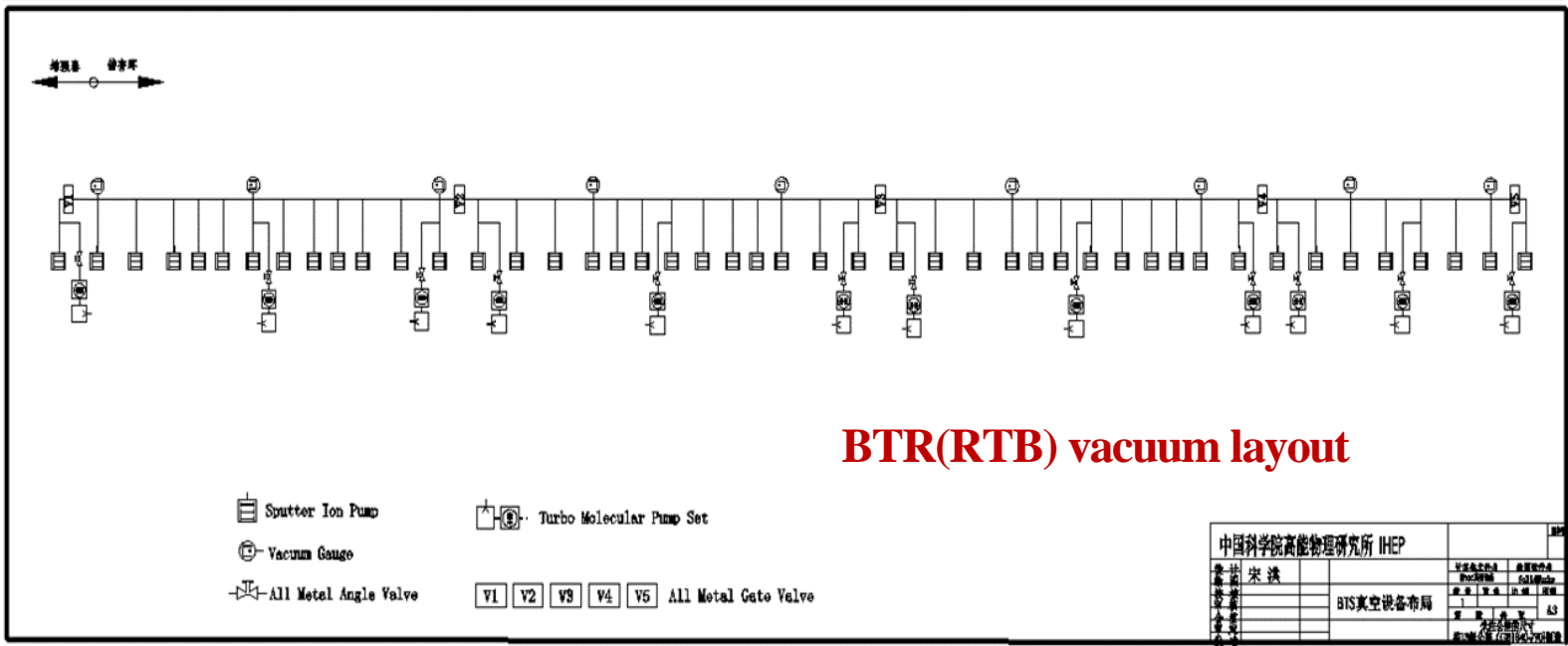
**LTB Line**

| Section  | Length/m | Average pressure /Torr | Maximum pressure /Torr | The distance of SIP |
|----------|----------|------------------------|------------------------|---------------------|
| LTB      | 25       | $2.3 \times 10^{-8}$   | $3.3 \times 10^{-8}$   | 2.5m                |
| BTS(STB) | 105      | $2.7 \times 10^{-8}$   | $4.7 \times 10^{-8}$   | 1.8m                |



**LTB vacuum layout**

Sputter Ion Pump     Turbo Molecular Pump Set  
 Vacuum Gauge  
 All Metal Angle Valve     All Metal Gate Valve



**BTR(RTB) vacuum layout**

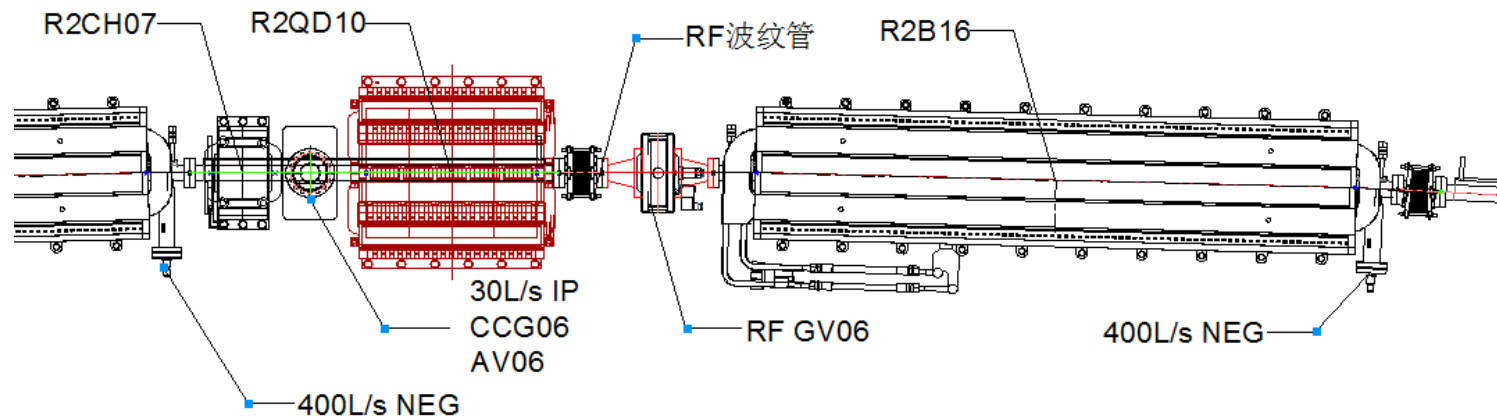
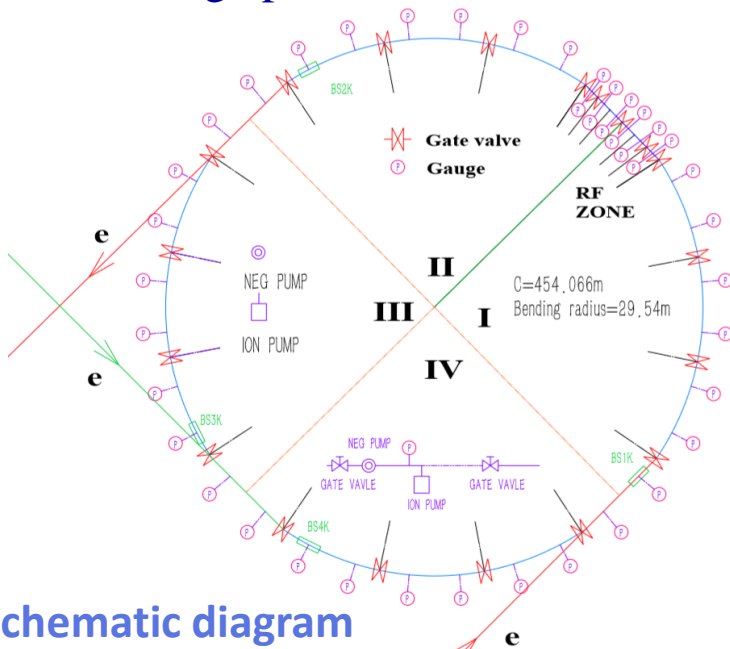
Sputter Ion Pump     Turbo Molecular Pump Set  
 Vacuum Gauge  
 All Metal Angle Valve     All Metal Gate Valve

|                   |       |
|-------------------|-------|
| 中国科学院高能物理研究所 IHEP |       |
| 设计 宋洪             | 审核 宋洪 |
| 制图 宋洪             | 审核 宋洪 |
| BTS真空设备布局         |       |
| 日期                | 4.3   |

# 3 Booster vacuum system

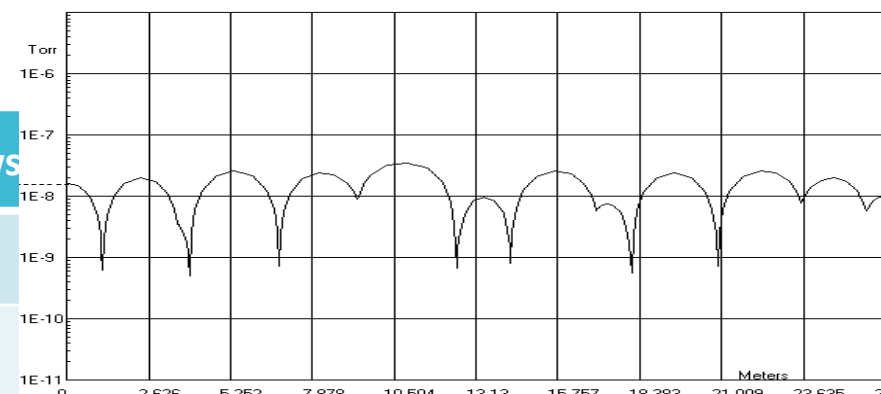
Pengcheng Wang

- The vacuum system is divided into 19 sections, 12 sections for the arc regions, 7 sections for the straight and RF regions. Each section has 2 rough pumping valves. The system is first pumped to  $10^{-7}$  Torr by oil-free TMPs. The ion pumps and NEG pumps will be used as maintain pumps. Average pressure is  $1.59 \times 10^{-8}$  Torr



schematic diagram

| Item          | Ion pump | NEG pump | Gate valve | Vacuum gauge | RGA | RF-shield Bellows |
|---------------|----------|----------|------------|--------------|-----|-------------------|
| Quantity      | 140      | 84       | 19         | 38           | 16  | 152               |
| Specification | 30 L/s   | 400 L/s  | All metal  | CCG          |     | Double fingers    |

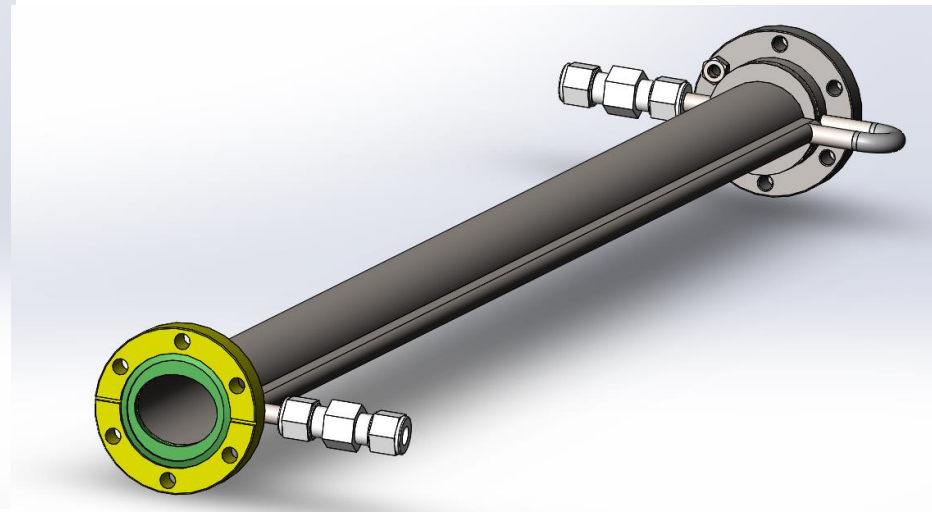
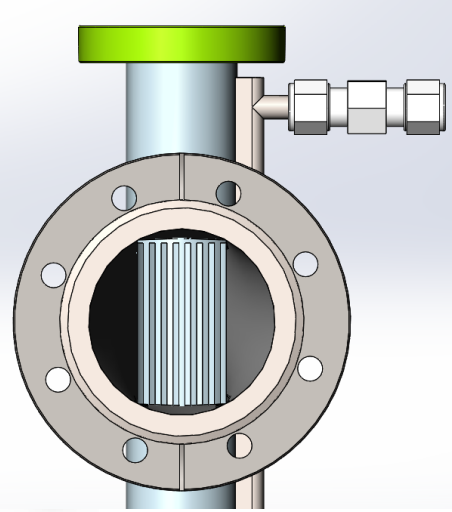
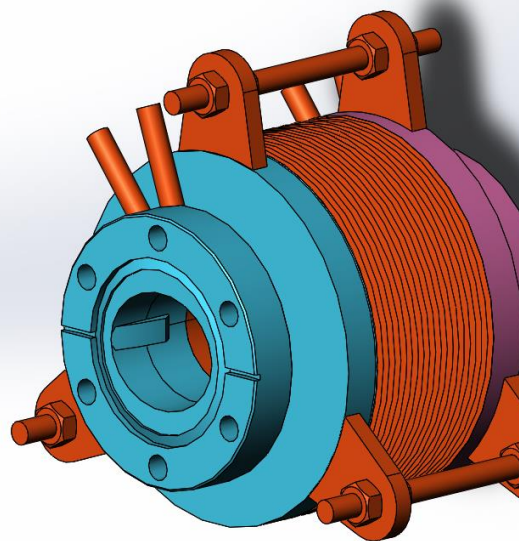
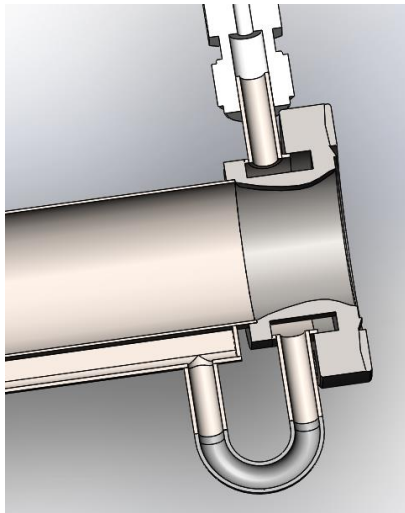




# 3 Booster vacuum requirements

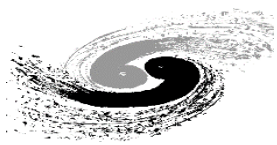
Jiaming Liu

- ◆ The in-line absorbers are used to prevent SR photons from falling on the bellows, BPM etc.

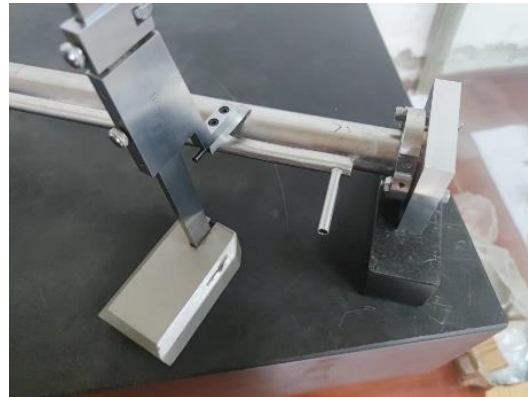
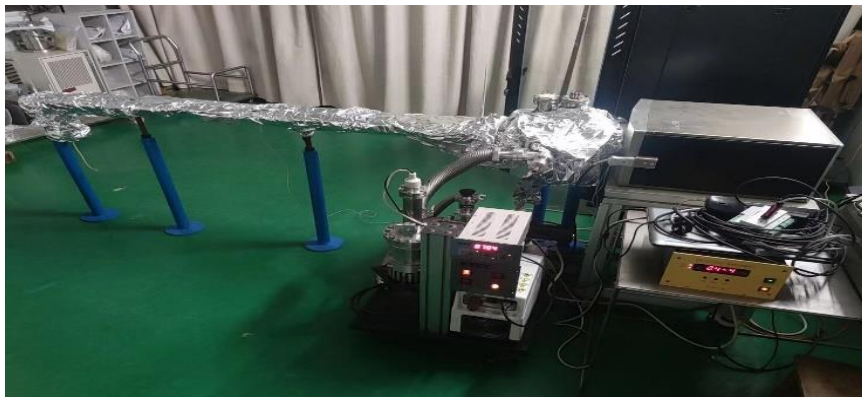
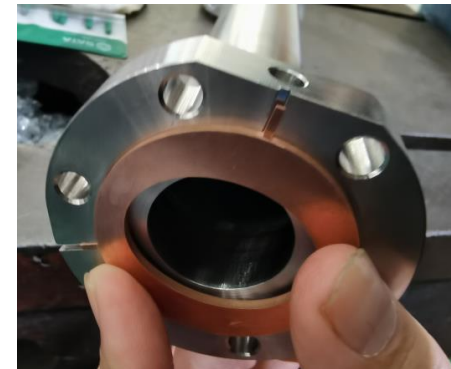
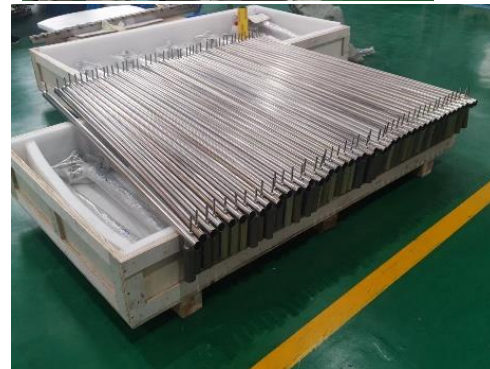
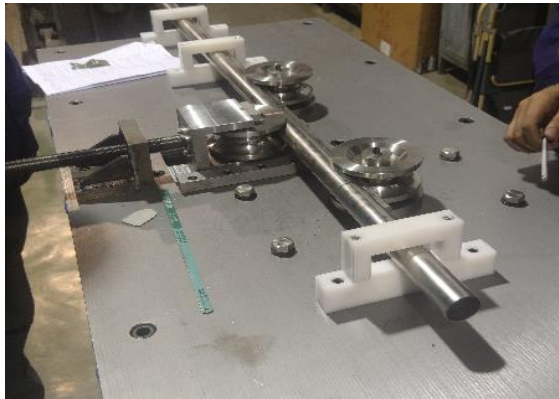


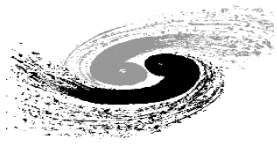
- ◆ In order to reduce the eddy current effect during the quick cycle of the magnets, the vacuum chambers will be made of thin-walled stainless steel. The inner surface of the vacuum chambers should be as smooth as possible to reduce the impedance.
- ◆ A cross-section of 36mm×30mm (H×V) ellipse with wall thickness of 0.7mm, length of 1.62m, bending radius of 28.52m. Permeability  $\leq 1.02$ .
- ◆ The peak SR power of the booster reaches 0.34 kW/m, and the average power is about 1/4 of the peak power.





# 3 Processes of vacuum chamber produce



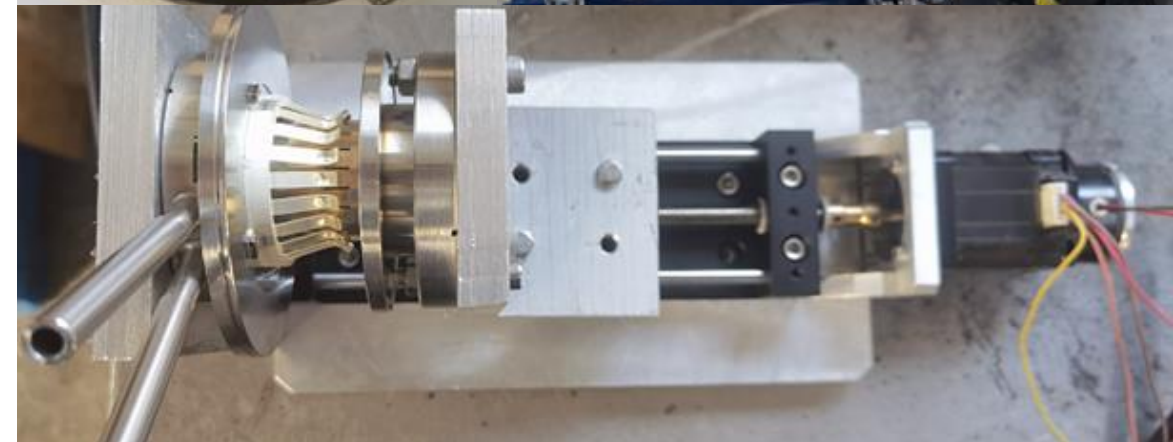
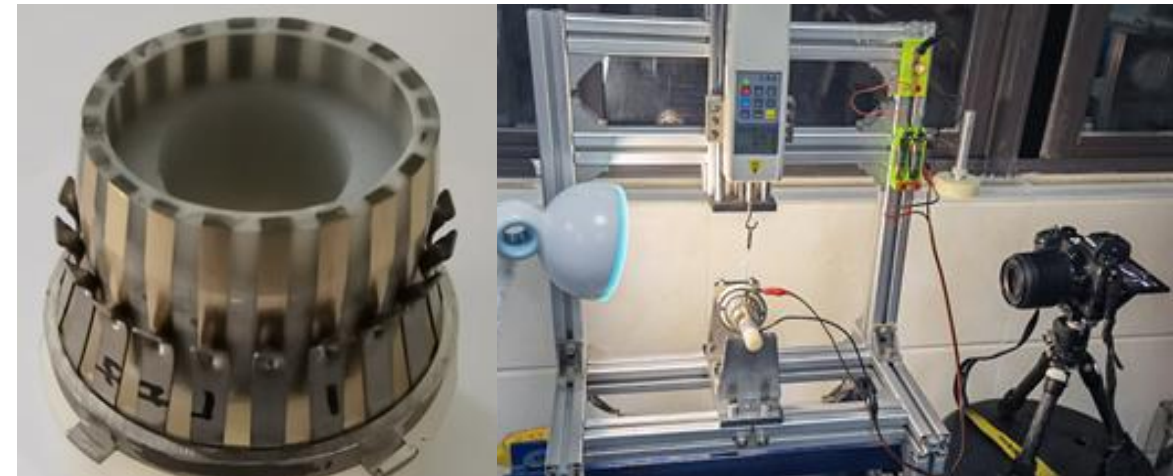
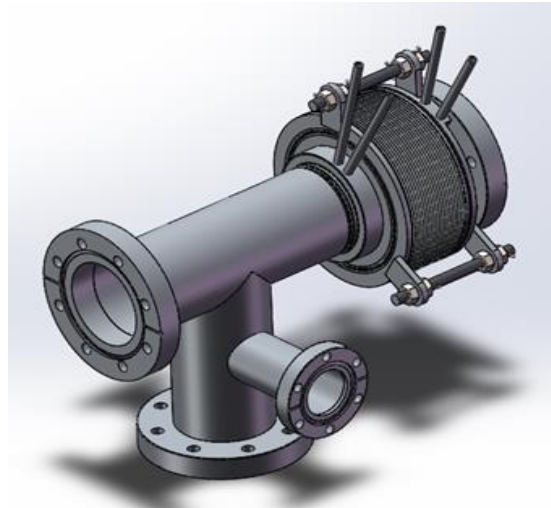
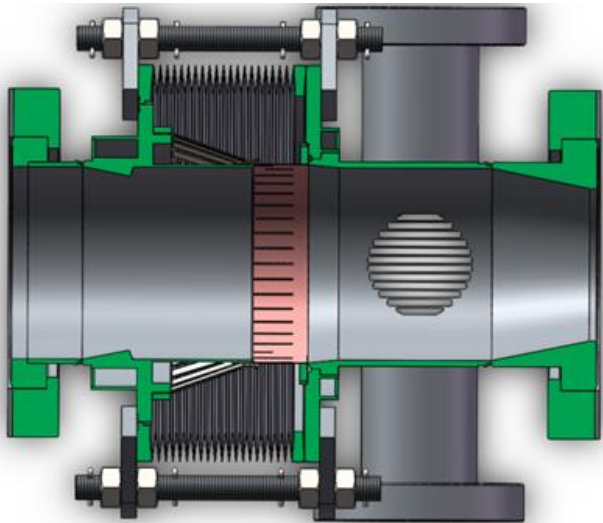


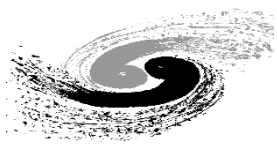
# 3 RF shielding bellows of booster

Jiaming Liu

| Total length | Expansion | Contraction | Ellipse cross section | Contact pressure | Maximum radial offset |
|--------------|-----------|-------------|-----------------------|------------------|-----------------------|
| 70-100mm     | 5mm       | 10mm        | 36mm×30mm             | 125±25g          | 2mm                   |

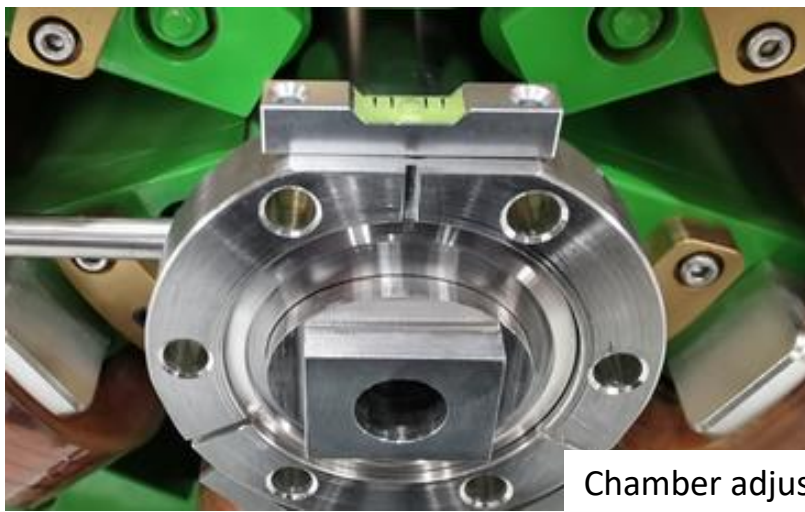
- ◆ Mask is designed on the upstream of RF bellows to absorb the SR
- ◆ The all RF bellows of HEPS is produced by domestic company in China



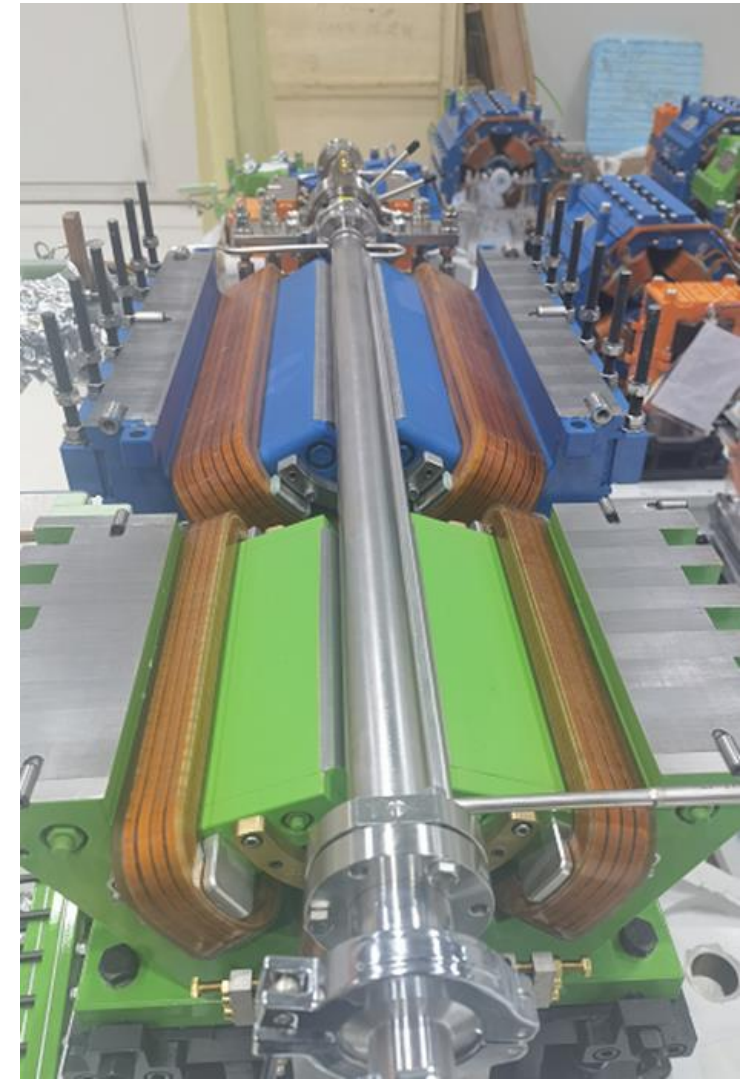
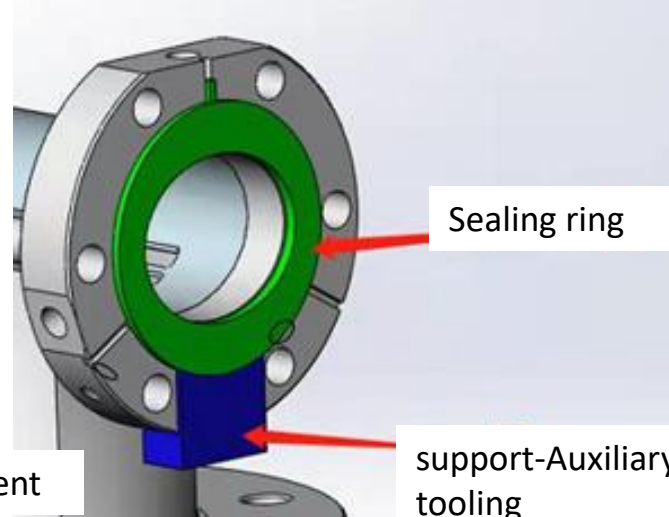


# 3 Booster vacuum components pre-installation at PAPS

Jiaming Liu xiaoyang Sun, Bangle Zhu



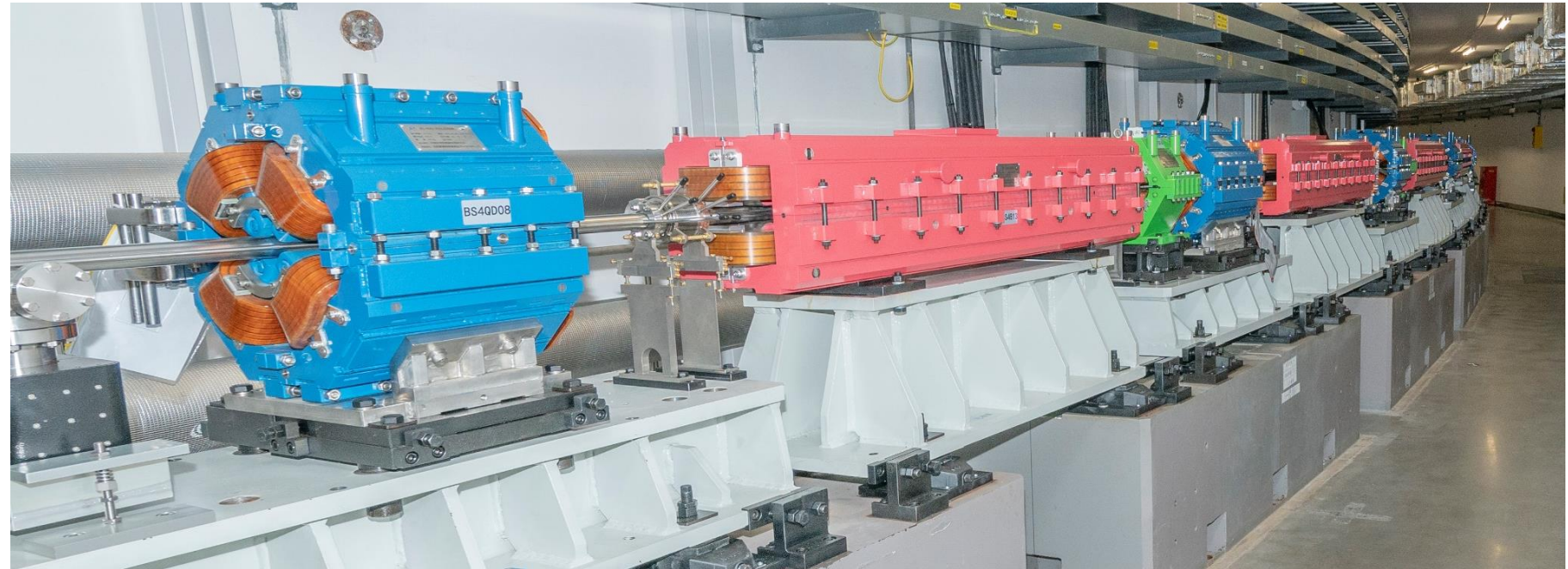
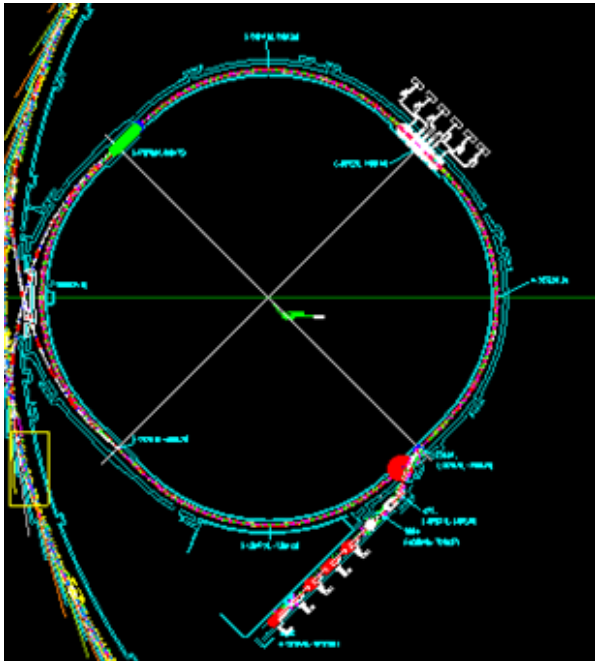
Chamber adjustment

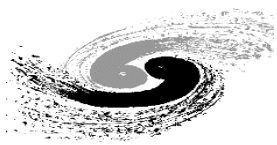




# 3 Status of Booster

- ◆ The installation of all devices of booster has been finished so far.
- ◆ The last chamber of vacuum system have been installed by 23th Jan 2023, which is before Chinese New Year. The vacuum will be pumped down after cables are connected.

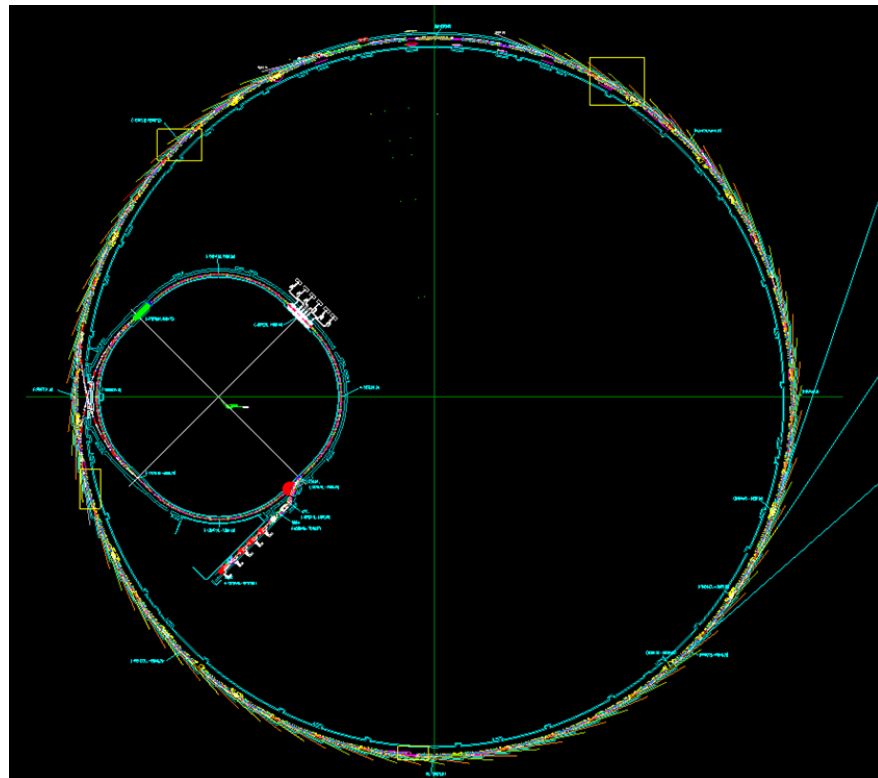
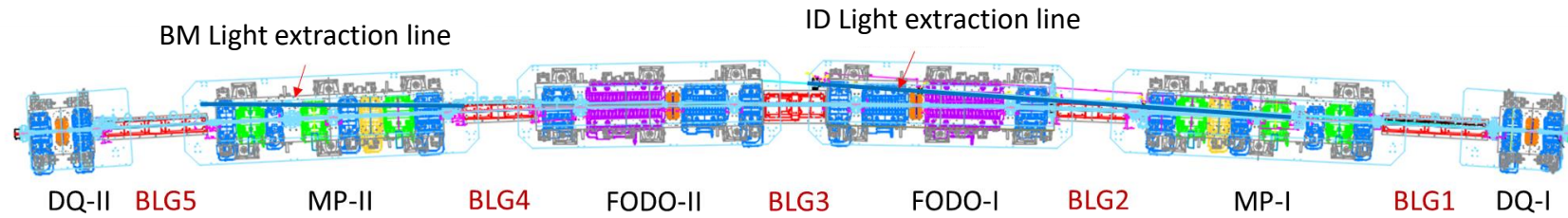




# 4. Storage ring Vacuum

Haiyi Dong

- ◆ The Circumference of **HEPS storage ring** is **1360.4 m**, and **24 double 7BA units** are applied in an achromatic Lattice design.
- ◆ The long linear section is located at the beginning of the **48 standard units** and is mainly used for mounting insertions, injection and extraction devices, RF and other equipment. RF shielding all-metal gate valves are installed on the two ends of the long linear section, which are divided into about **96 vacuum sections**.
- ◆ Each standard arc unit includes 18 vacuum chambers, the most of those will be NEG coating, and 14 RF shielded bellows, 4 photon absorbers, ion pumps, NEG pumps, vacuum gauges and valves.



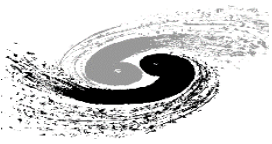
•R46 even arc unit



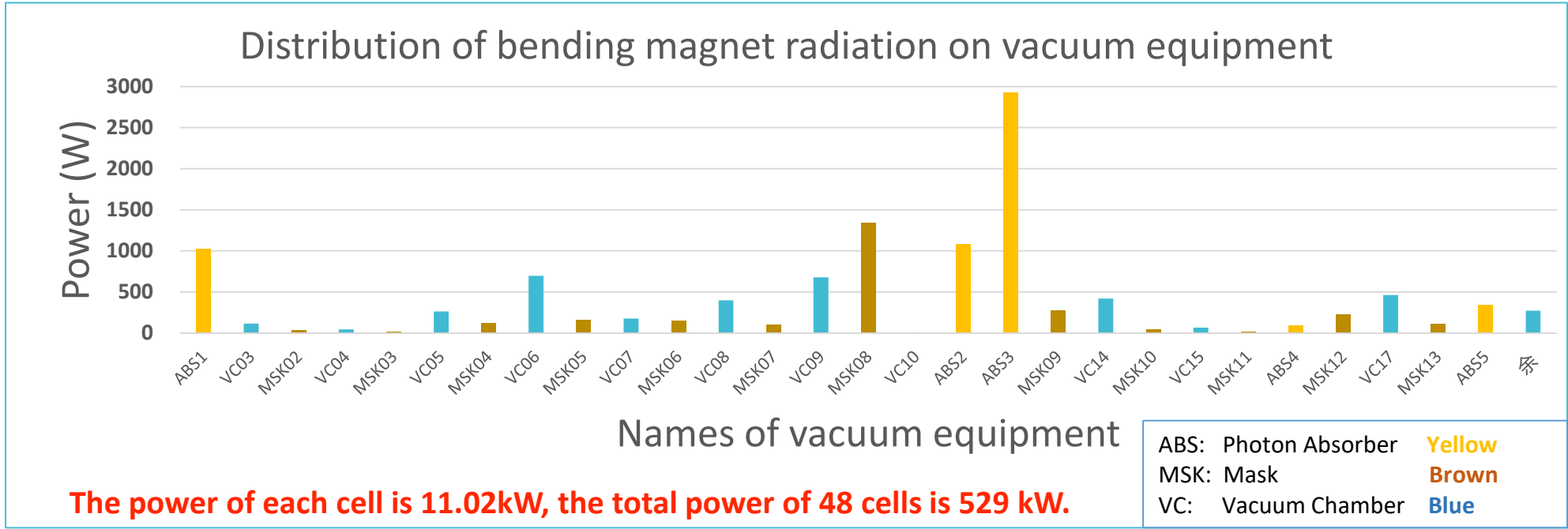
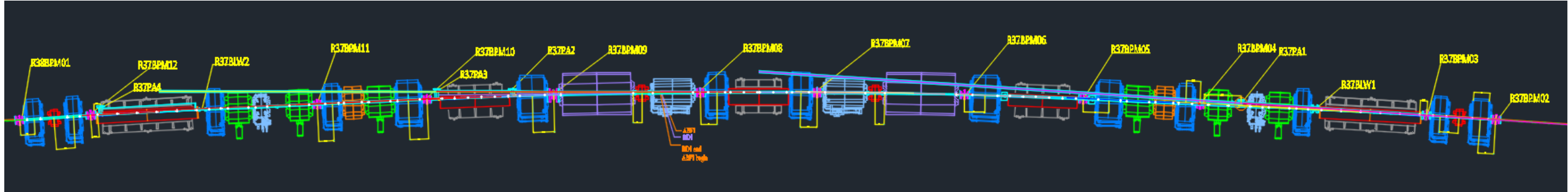


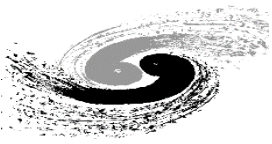
## 4. Storage ring Vacuum requirements

- A vacuum in the lower than  $1 \times 10^{-9}$  Torr is required when a beam is circulating in the storage ring. It can be shown that the beam lifetime would exceed 100 h if only losses due to Interactions between beam and gas.
- Good beam lifetime must be achieved soon after the initial startup with a stored beam.
- The system must be capable of quick recovery after the sections are vented for maintenance.
- The chamber wall is designed as smooth as possible to minimize the electromagnetic fields induced by the beam.
- Sufficient cooling to safely dissipate the heat load associated with both synchrotron radiation and higher-order-mode (HOM) losses.
- Capability to shield outer ring components from synchrotron radiation.



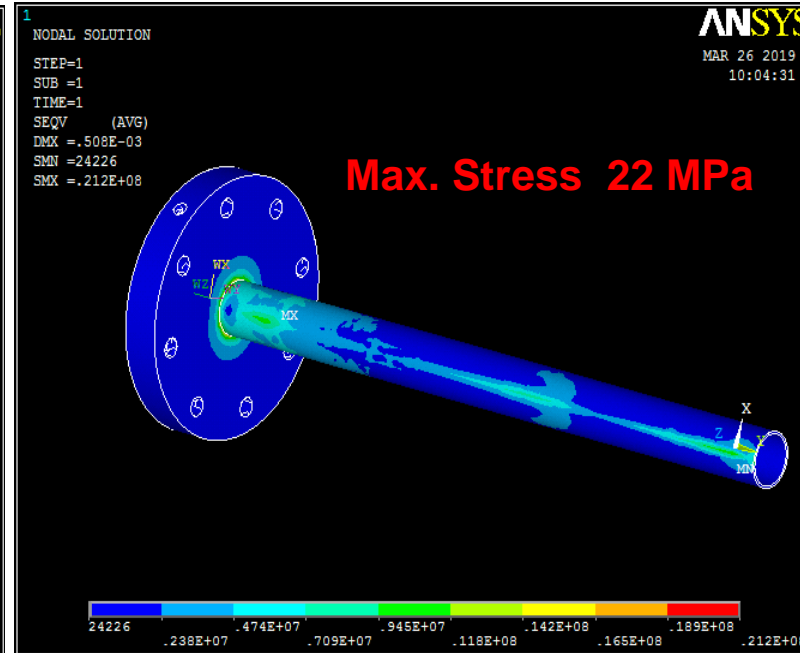
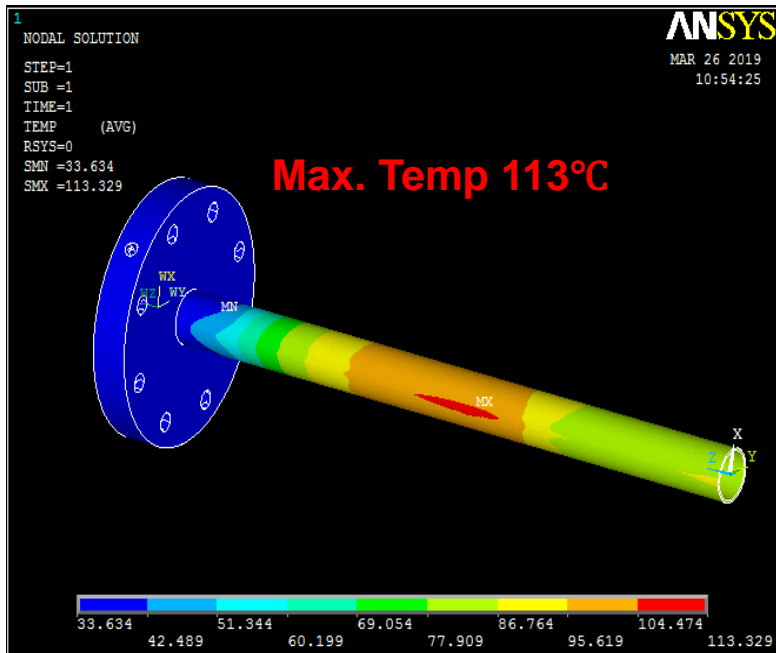
# 4. Distribution of SR power on the Storage Ring vacuum components



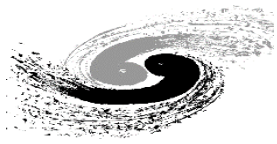


# 4. FEA of the mask of a highest power density

| Positions | Power (W) | Length (mm) | Height (mm) | Area (mm <sup>2</sup> ) | Power density (W/mm <sup>2</sup> ) |
|-----------|-----------|-------------|-------------|-------------------------|------------------------------------|
| I         | 297.92    | 101.24      | 0.2         | 20.25                   | 14.71                              |
| I I       | 839.11    | 164.77      | 0.2         | 33                      | 25.46                              |
| I I I     | 129.6     | 19.18       | 0.2         | 3.84                    | 33.79                              |
| I V       | 14.93     | 2.8         | 0.14        | 0.39                    | 38.07                              |
| V         | 8.6       | 3           | 0.14        | 0.42                    | 20.47                              |



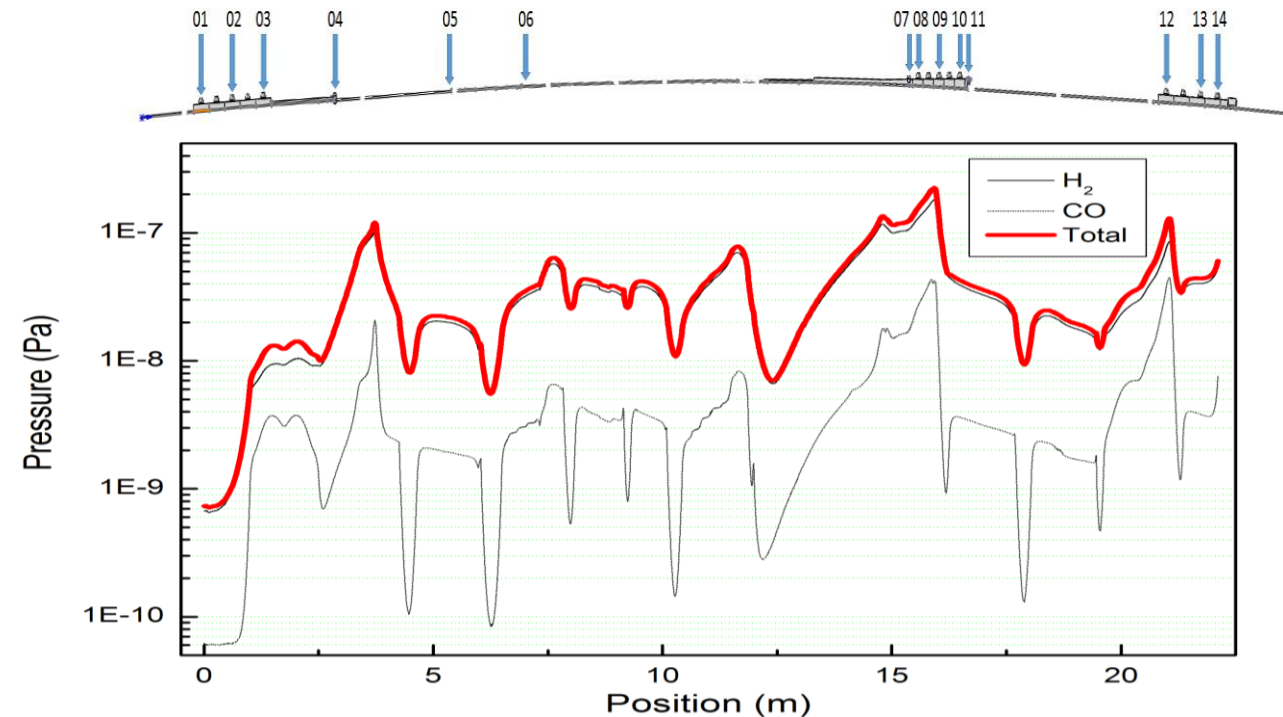
- SR Mask with a slope length of 300 mm (total of I To V) to reduce power density.
- The part of mask in the magnet is cooled by water-cooled pipes and the outer part by water-cooled jackets.
- As the total power does not decrease, the maximum temperature is still high.



## 4. Pumping system & vacuum distribution

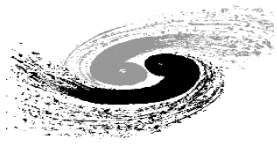
- The circumference of the storage ring is divided into about 96 sectors by means of the RF all metal gate valves, which allow all vacuum work such as pumping down from atmosphere pressure, leak detecting, bakeout, and vacuum interlock protection, to be done in sections of manageable length and volume.
- Roughing down to approximately  $10^{-7}$  Torr will be achieved by the oil free turbo-molecular pump group.
- **The main pumping is achieved with Non Evaporable Getter(NEG)-coated chambers, the ion pumps will be used to maintain pressure and pump off  $\text{CH}_4$  and noble gases.**
- **CPMU, IVU and RF cavities will be pumped down by NEG pumps and ion pumps.**

1~14: ion sputtering pump



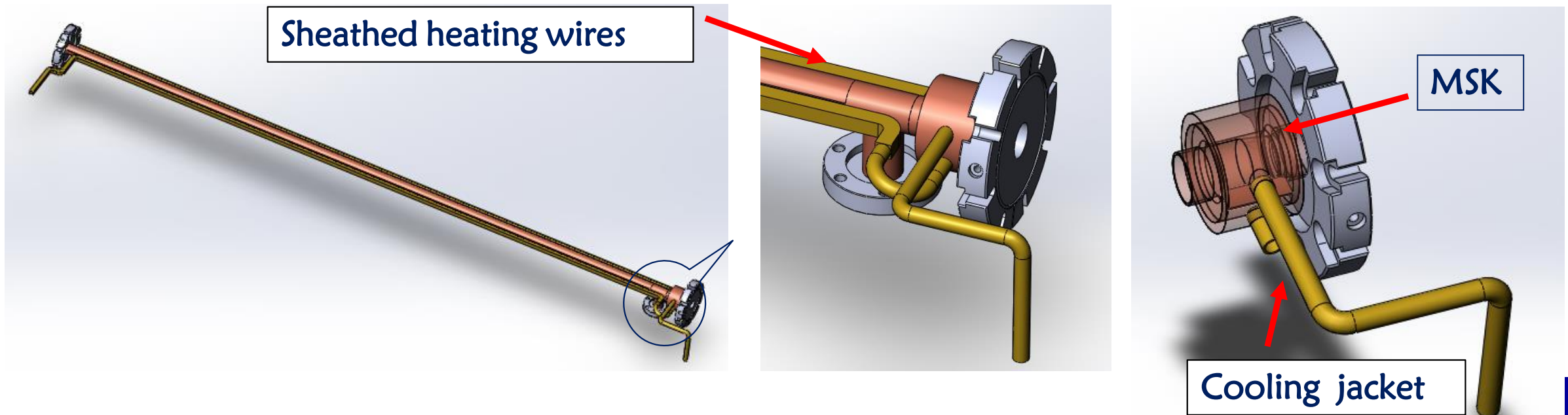
Pressure profile of a standard arc section @ 6GeV, 200mA

- Thermal outgassing rate:  $2.5 \times 10^{-12}$  mbar·L/s·cm<sup>2</sup>
- Photo desorption rate:  $1.95 \times 10^{-6}$  molecules/photon
- Pumping speeds: Ion pump 30 L/s;
- NEG film sticking factor H<sub>2</sub> is 0.007, CO is 0.07



## 4. Vacuum chambers requirements

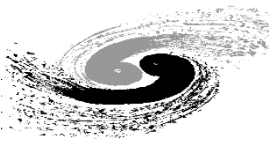
- Cu-Cr-Zr (C18150) is chosen as the chambers material because of its higher thermal conductivity and higher resistance to softening due to the NEG activation temperature of 200 C°.
- Stainless steel (Inconel) material is used for fast corrector chambers and some chambers with ion pumps.
- The vacuum chambers have a 22 mm inside diameter with 1 mm wall thickness. The clearance between the chambers and the magnets poles is 1 mm (include 0.4mm heating tape).
- Distributed cooling channels are welded to the chambers to safely dissipate the SR power.
- All the chambers are produced with tight mechanical tolerances to avoid any interference with the magnet poles and coils.



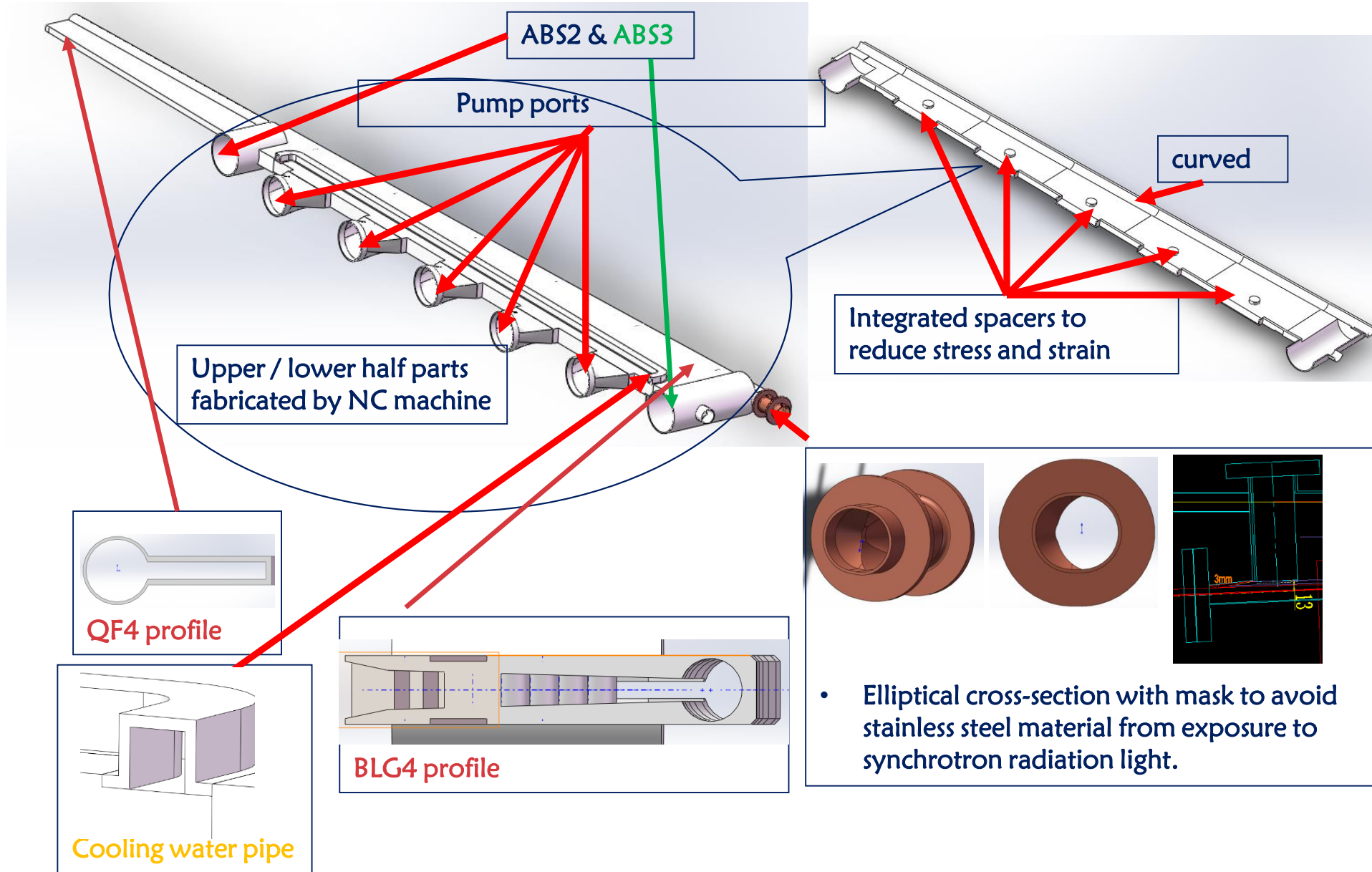


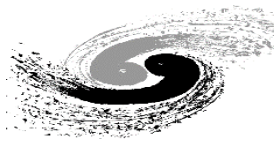
# Vacuum chambers of a 7BA cell

| Number | Related magnets  | Shape              | Material           | Length (mm) | Bending ( ° ) | Flange types |
|--------|------------------|--------------------|--------------------|-------------|---------------|--------------|
| VC1    | QF1-FC1-QD1      | φ24*1              | C18150/Inconel625  | 956.9       |               | Various      |
| VC2    | BLG1             | Antechamber (part) | 316LN (coating Cu) | 1604.4      | 1.2372        | CF63         |
| VC3    | QD2-SD1-ABF1     | Antechamber/φ24*1  | C18150 (Cu-Cr-Zr)  | 1155.3      | 0.0768        | CF63/CF25    |
| VC4    | SF1              | φ24*1              | C18150             | 496.8       |               | CF25/CF63    |
| VC5    | QF2-OCT1-SD2-QD3 | φ24*1              | C18150             | 1667.8      |               | CF63         |
| VC6    | BLG2-QF3         | φ24*1              | C18150             | 1697.8      | 0.8375        | CF63         |
| VC7    | BD1              | φ24*1              | C18150             | 1196.9      | 1.3671        | CF63/CF25    |
| VC8    | FC2              | φ24*1              | Inconel625         | 221.3       |               | CF25/CF25    |
| VC9    | ABF2             | φ24*1              | C18150             | 715.2       | 0.2756        | CF25/CF63    |
| VC10   | QD4-BLG3-QD5     | φ24*1              | C18150             | 1666.7      | 1.3863        | CF63         |
| VC11   | ABF3             | Antechamber        | C18150             | 705.2       | 0.3081        | CF63         |
| VC12   | FC3              | Antechamber        | Inconel625         | 221.3       |               | CF63         |
| VC13   | BD2              | Antechamber        | C18150             | 1168        | 1.3675        | CF63/CF160   |
| VC14   | BLG4-QF4         | Antechamber (part) | 316LN (coating Cu) | 1808.4      | 0.8142        | CF160/CF63   |
| VC15   | QD6-SD3-OCT2-QF5 | φ24*1              | C18150             | 1555.8      |               | CF63         |
| VC16   | SF2-ABF4-SD4-QD7 | φ24*1              | C18150             | 1647.1      | 0.1178        | CF63/CF25    |
| VC17   | BLG5             | Antechamber (part) | 316LN (coating Cu) | 1589.1      | 1.288         | CF25/CF63    |
| VC18   | QD8-FC4-QF6      | Antechamber/φ24*1  | C18150/Inconel625  | 967.8       |               | Various      |



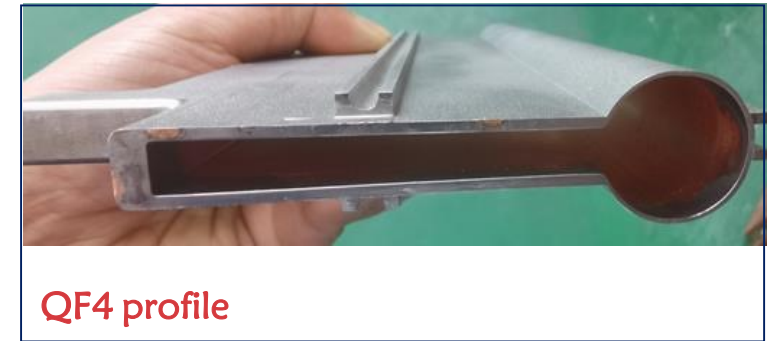
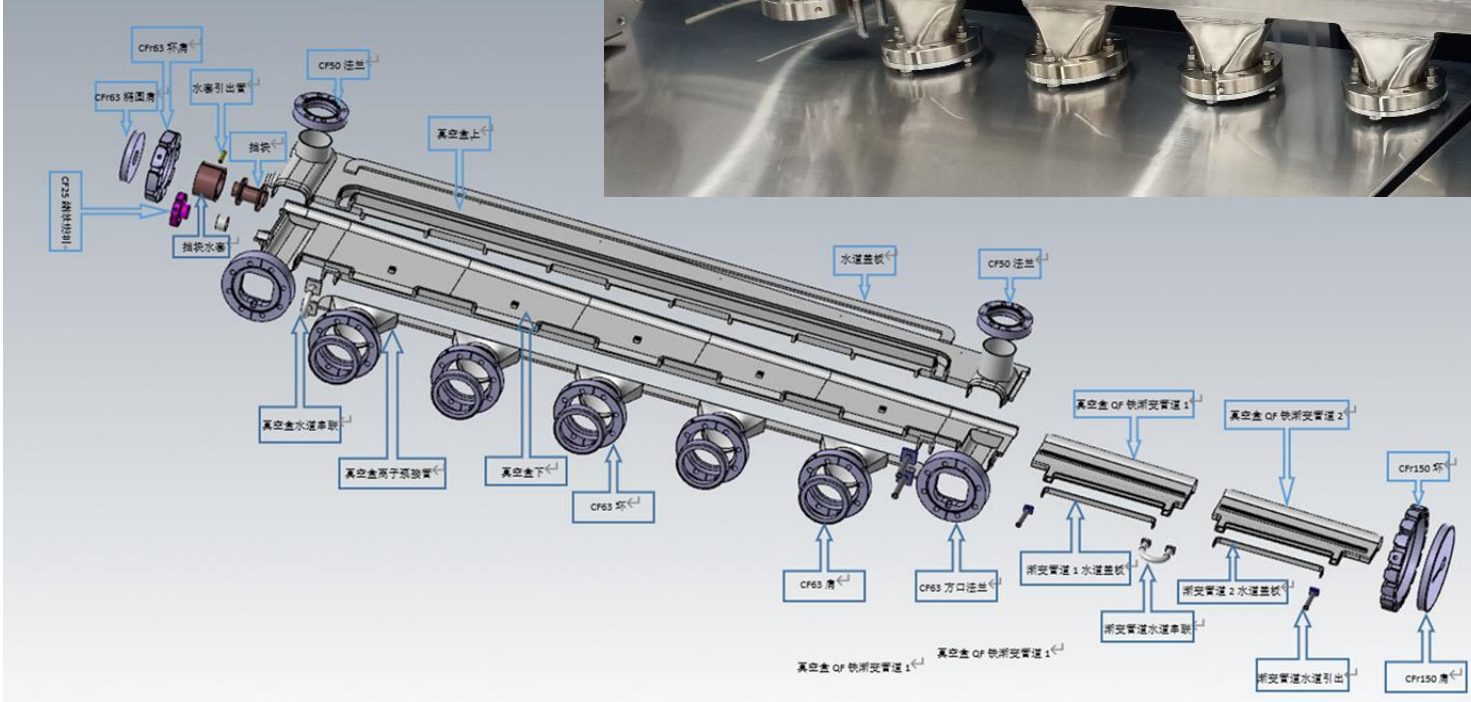
# Vacuum chamber design of VC14 (BLG4+QF4)





# Vacuum chamber design of VC14 (BLG4+QF4)

Dizhou Guo



QF4 profile

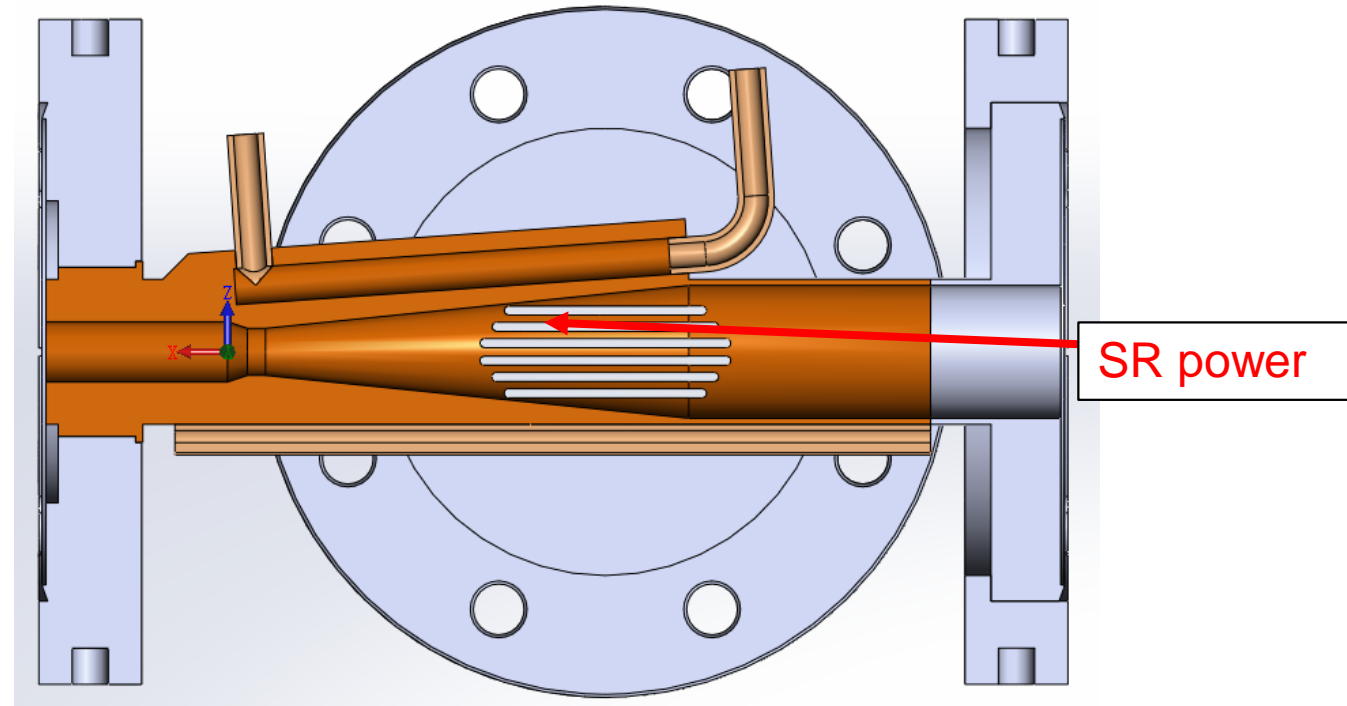
- ◆ VC14 consisted by BLG4, QF4, mask, tapered pipe, antechamber, pump ports
- ◆ Cu film of 20 μm coated on the beam pipe of S.S, Permeability  $\leq 1.02$
- ◆ Laser welding, electron beam welding, argon arc welding are employed





# Insertion vacuum chamber

Lei zhang



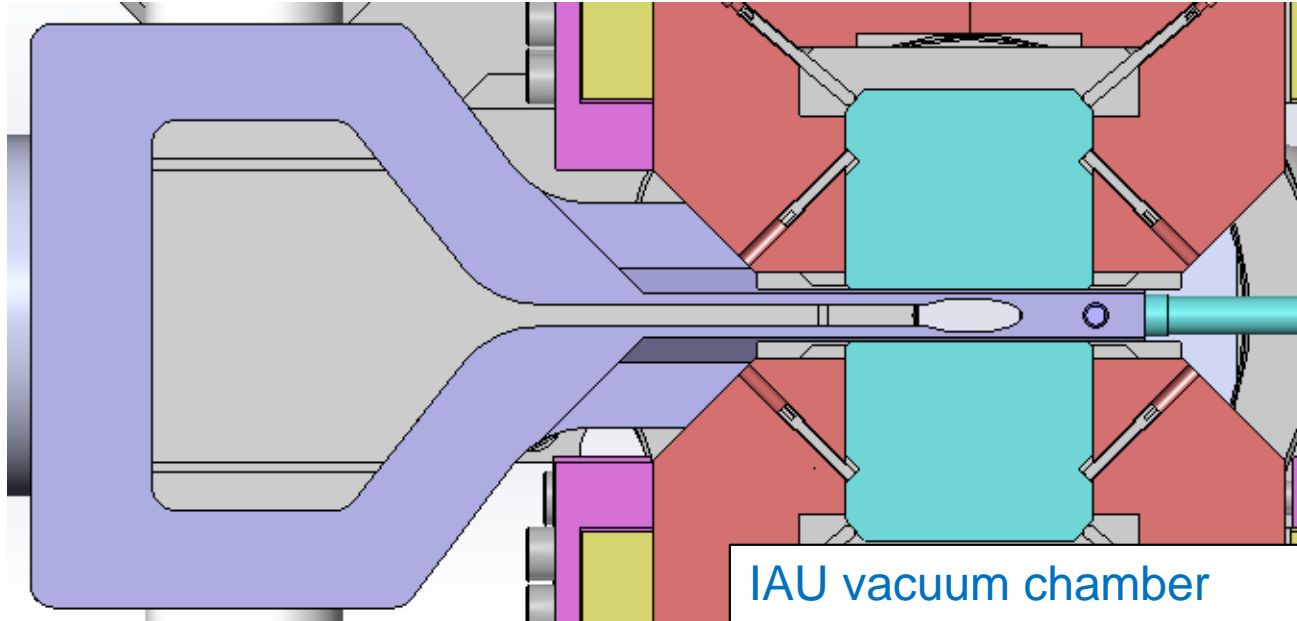
- Mango Wiggler vacuum chamber is made by extruded CuCrZr (C18150). The length is 2.4m, inner diameter is 8mm
- NEG coating, and no cooling pipe, due to low power of SR.

- Mango Wiggler upstream mask vacuum chamber is made by extruded CuCrZr (C18150). The length is 0.17m, inner diameter is varies from 7.8mm to 22mm.
- SR power is  $3\text{W}/\text{mm}^2$ , NEG coating and water cooling is applied.

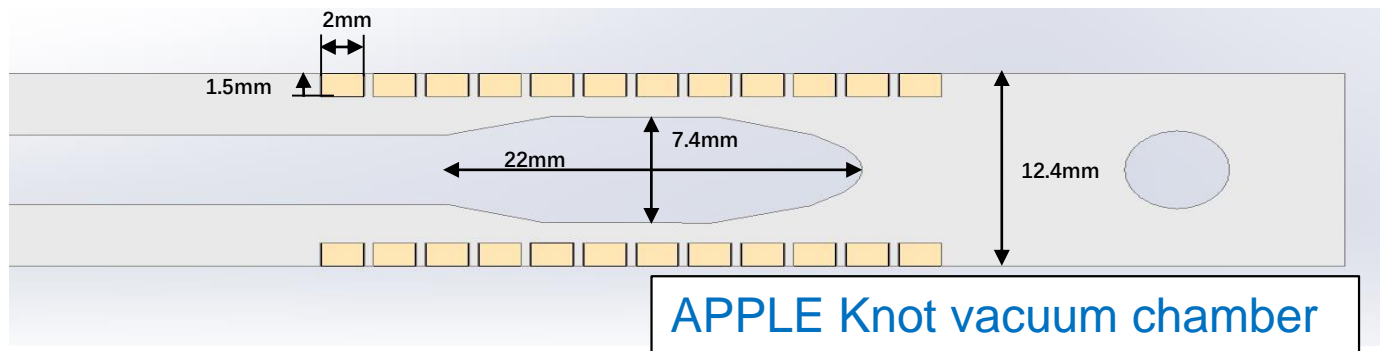


# Insertion vacuum chamber

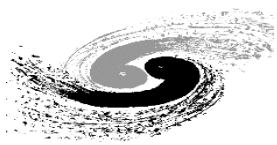
Lei zhang



- IAU vacuum chamber is made by extruded Al6061, the length is 5.4m, elliptical beam aperture  $7.4 \times 22$ .



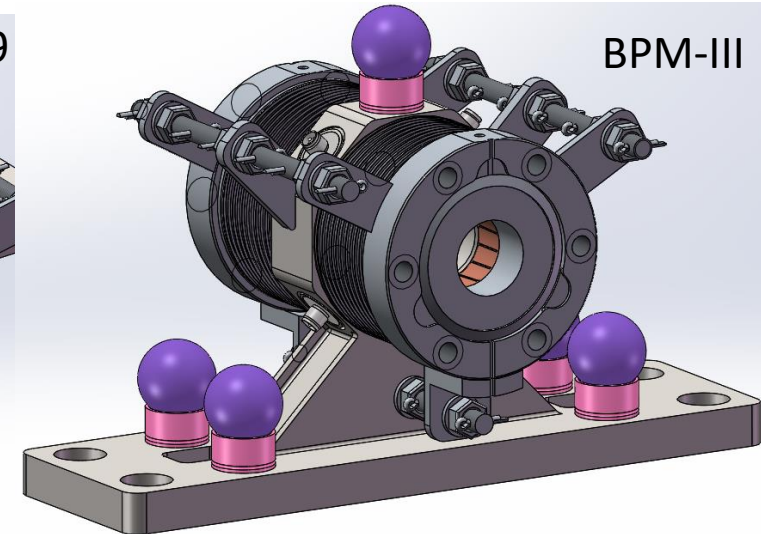
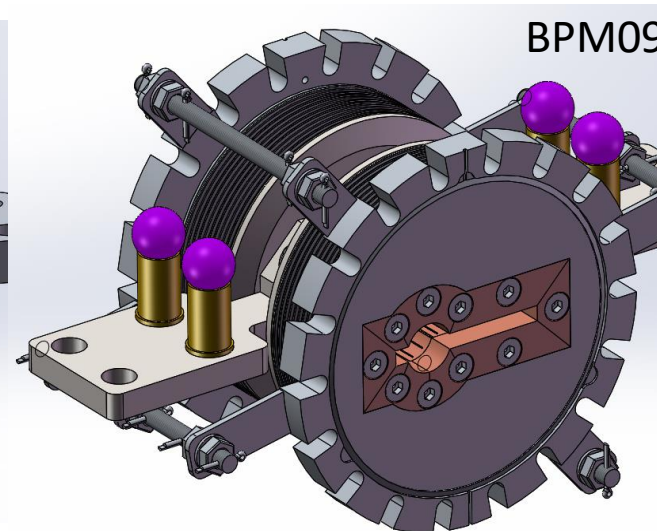
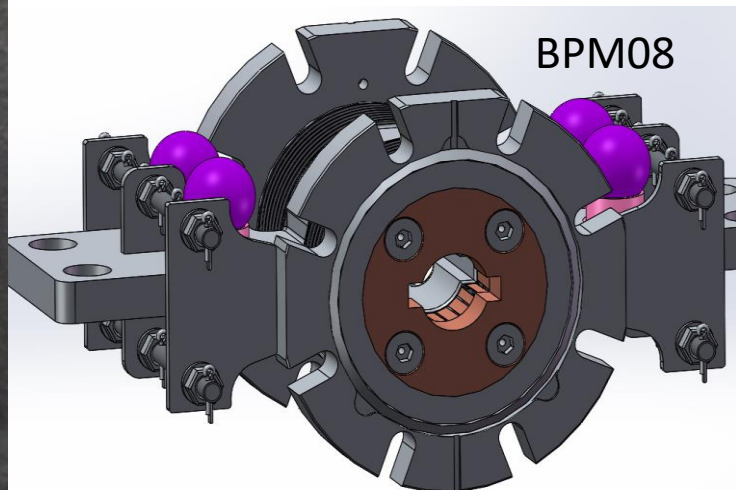
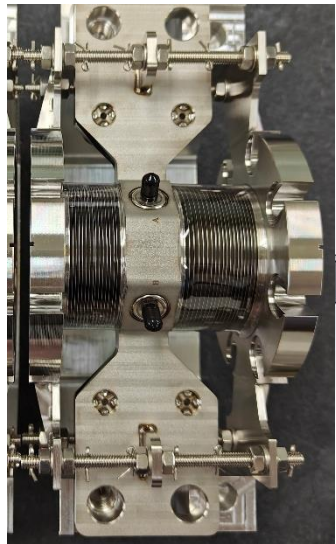
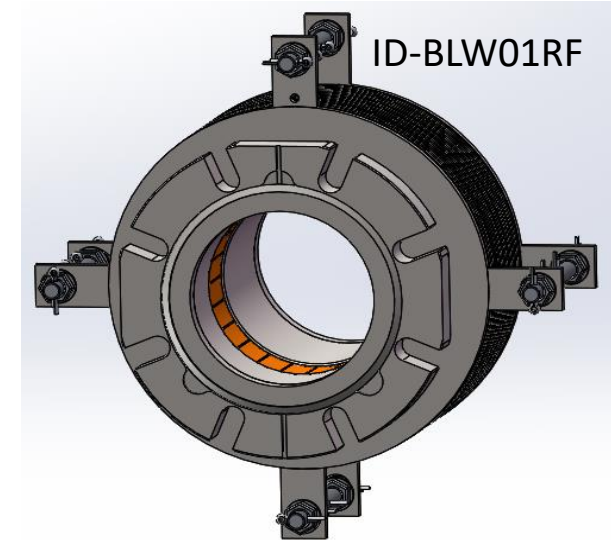
- APPLE Knot is the same as IAU vacuum chamber, which is made by extruded Al6061, the length is 5.4m, elliptical beam aperture  $7.4 \times 22$ .

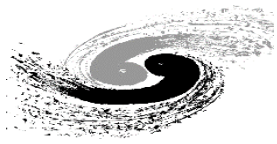


# RF shielding bellows of storage ring

Xujian Wang

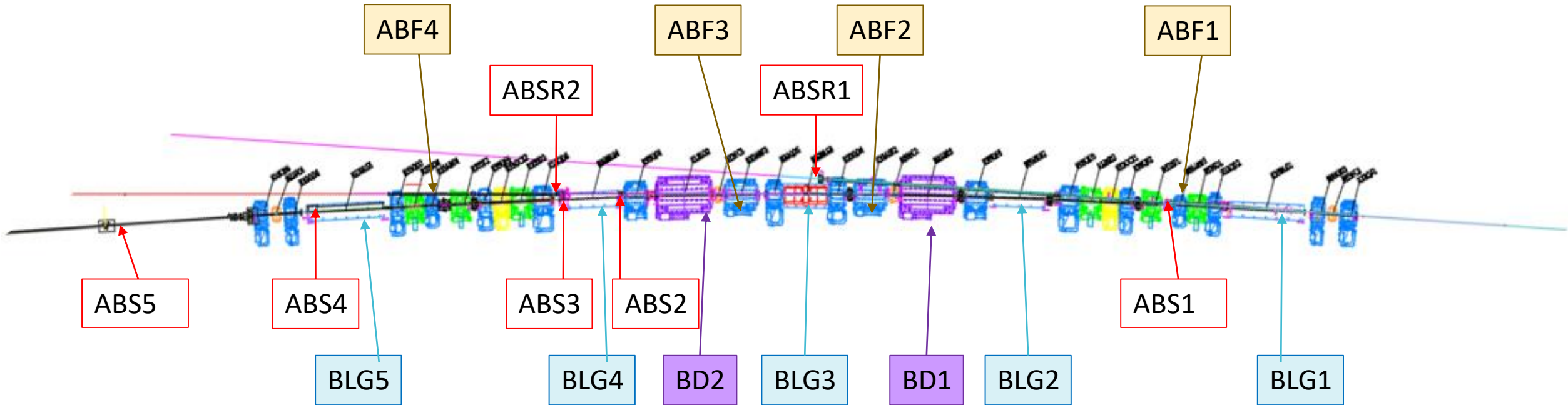
- ◆ Vacuum bellow modules are needed to compensate the mechanical misalignments of the vacuum chambers during installation and to absorb their thermal expansion during the bake-out. In order to reduce the beam impedance during operation with beams these modules are equipped with RF bridges to carry the image current.[1]
- ◆ BPM and RF shielding bellow are constructed into a whole to save space.



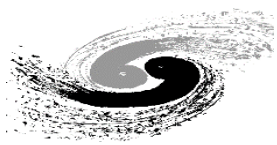


# Photon absorber Vs position of magnet

Qi Li

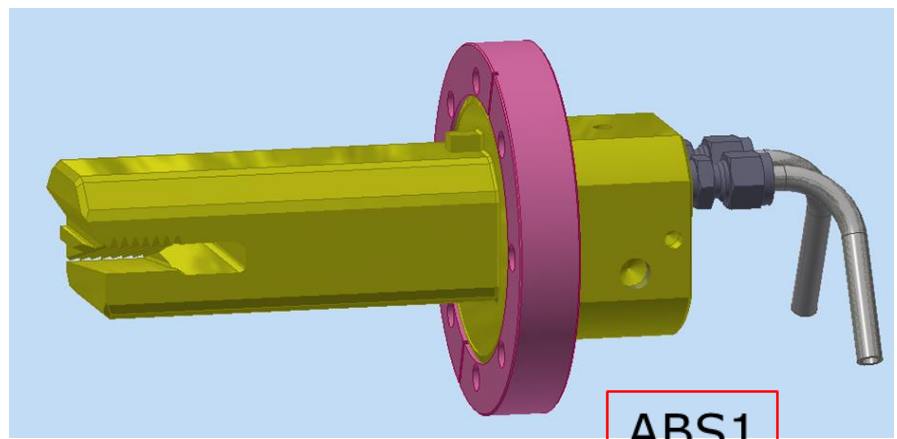
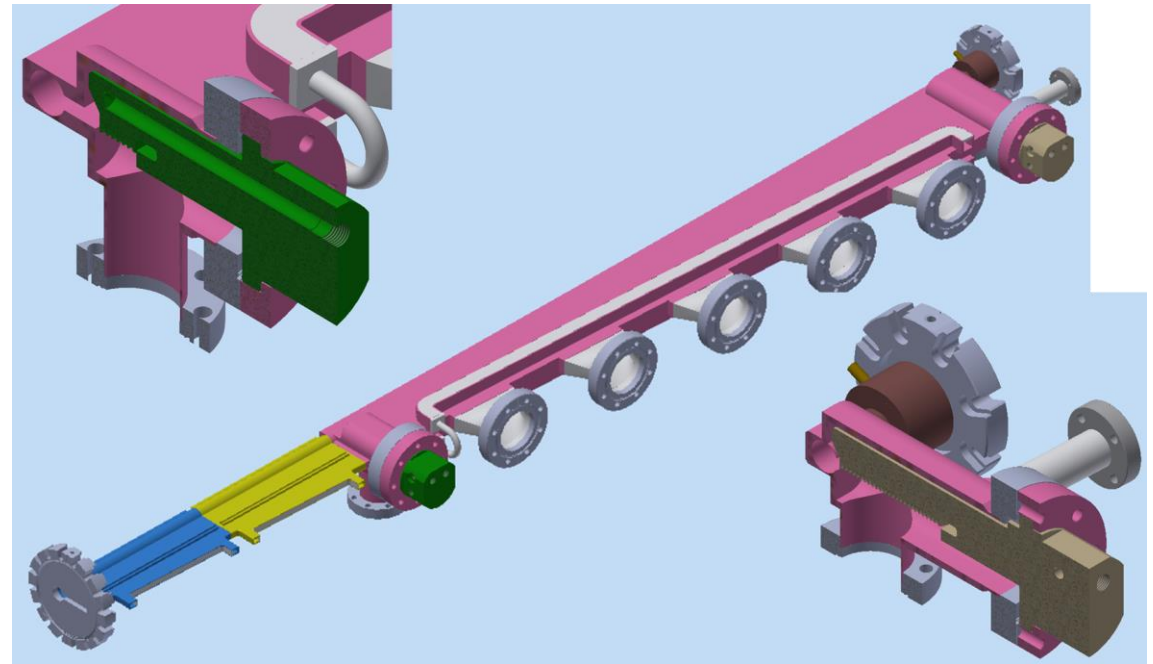
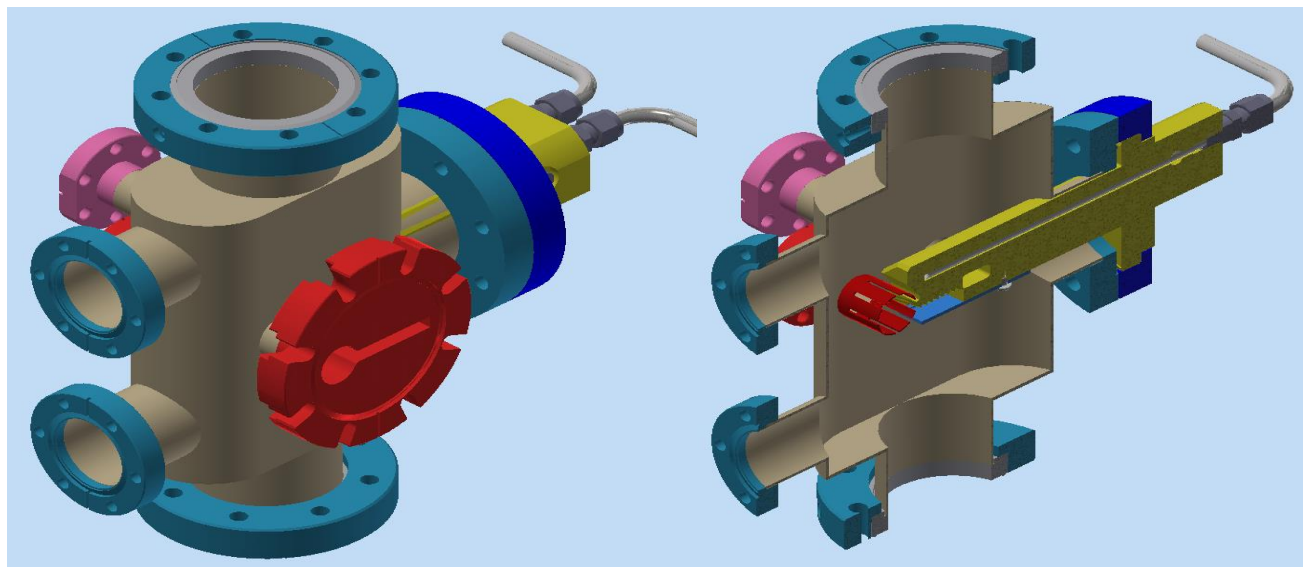


- ◆ About 41~48% of the synchrotron radiation power generated by the bending magnet is deposited on the photon absorber (ABS).
- ◆ Four photon absorbers were set up in the arc area of each unit, three of which were located at the exit of synchrotron radiation to extract the beam lines.
- ◆ Absorbers bear high power density synchronous light deposition, requiring good machining and installation accuracy.

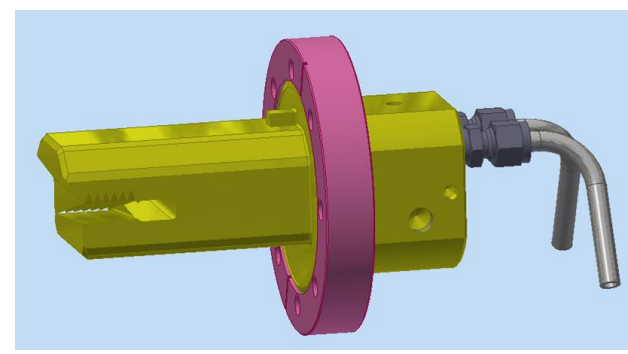


# Photon absorber models

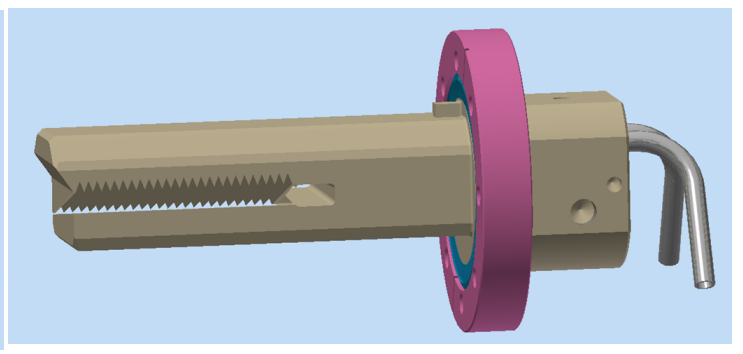
Qi Li



ABS1



ABS2



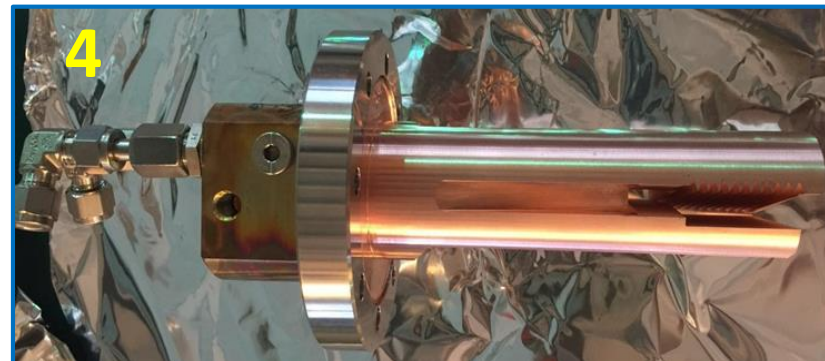
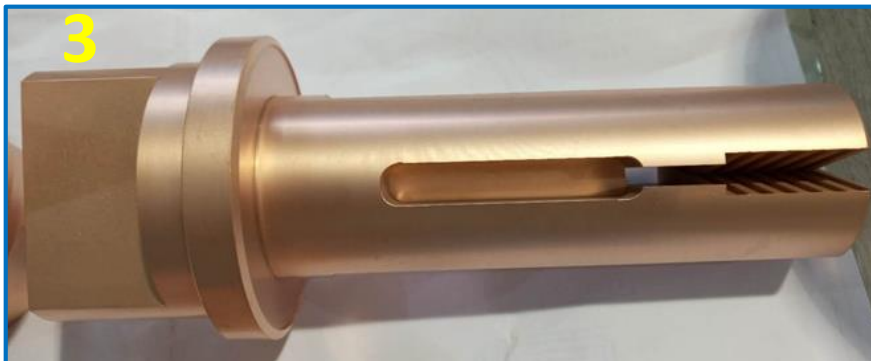
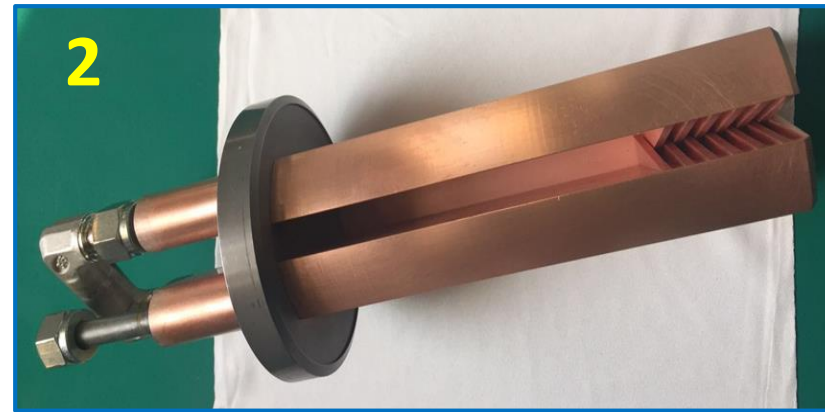
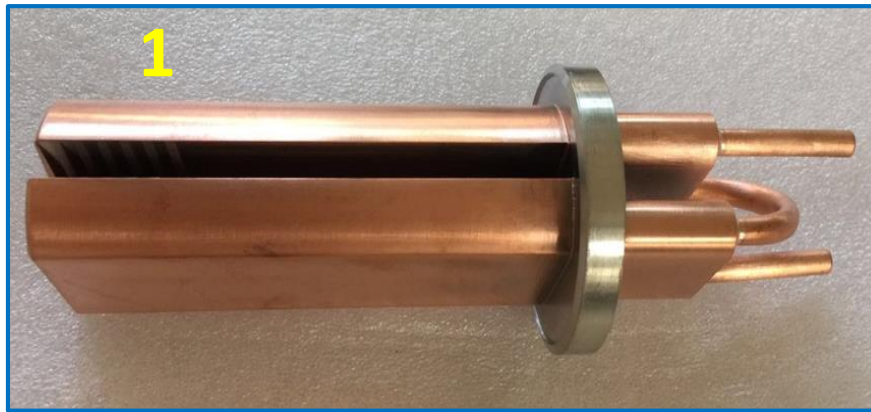
ABS3

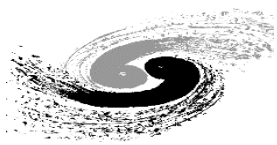


# Photon absorber prototypes

Qi Li

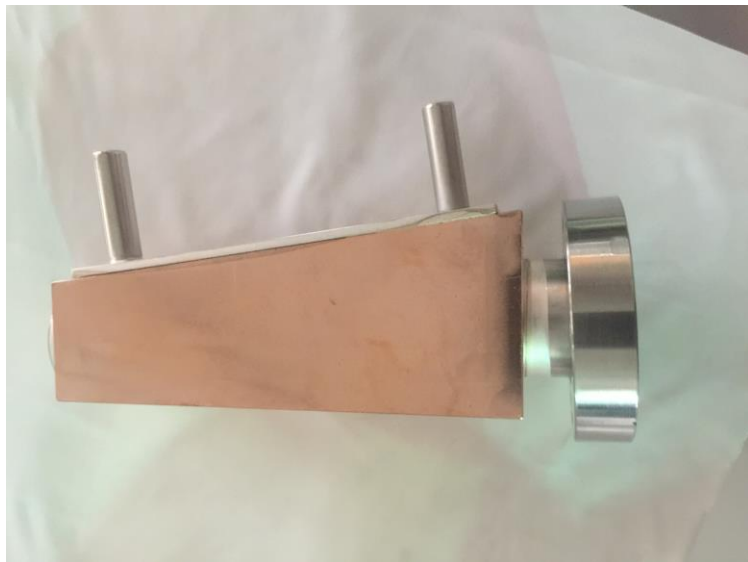
- 1 GlidCop-AL15 and SS316L flange brazing in a vacuum furnace.
- 2 GlidCop-AL15 and SS316L flange brazing in a hydrogen furnace.
- 3 and 4 CuCrZr copper Integrating flange (no brazing).

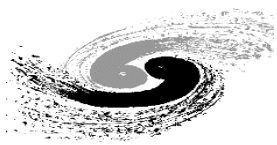




# Photon absorber prototypes

Qi Li

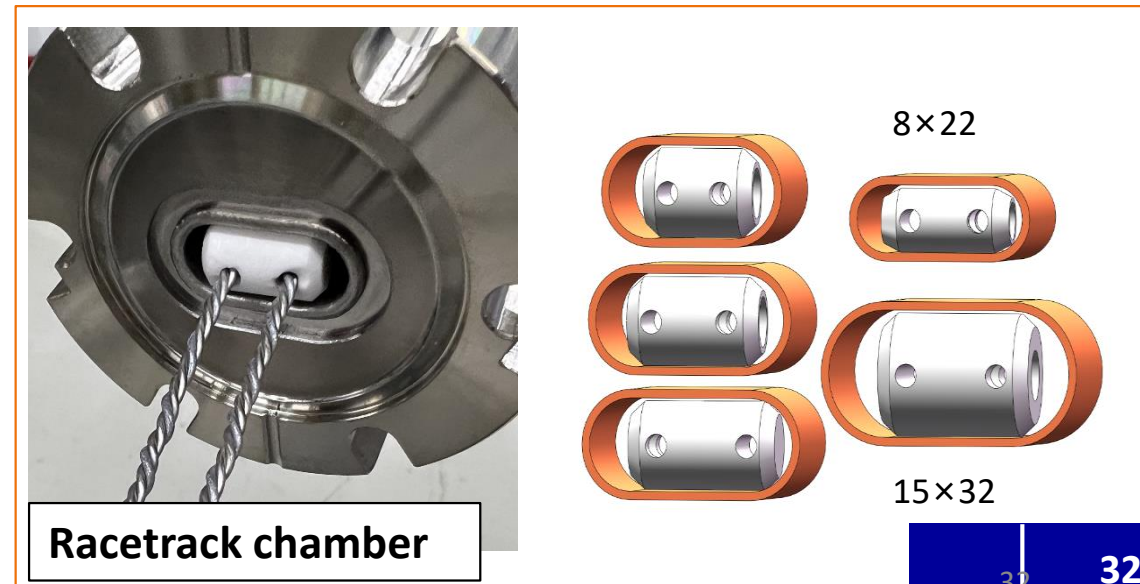
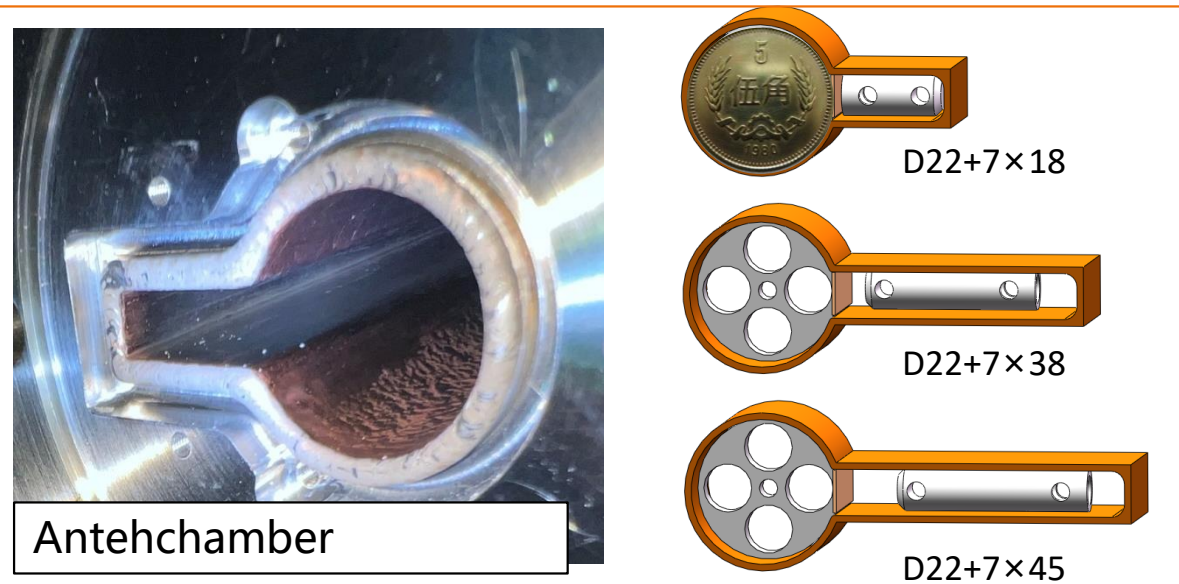
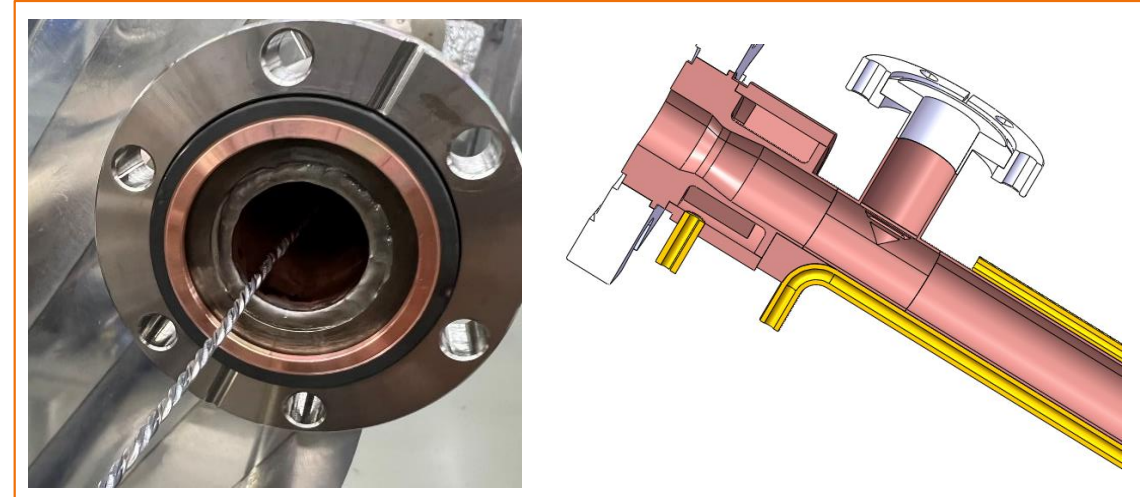
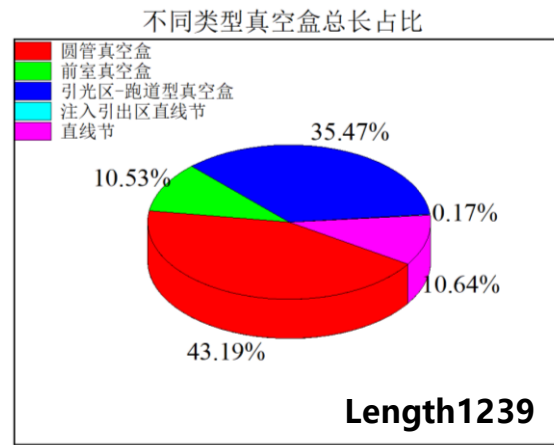
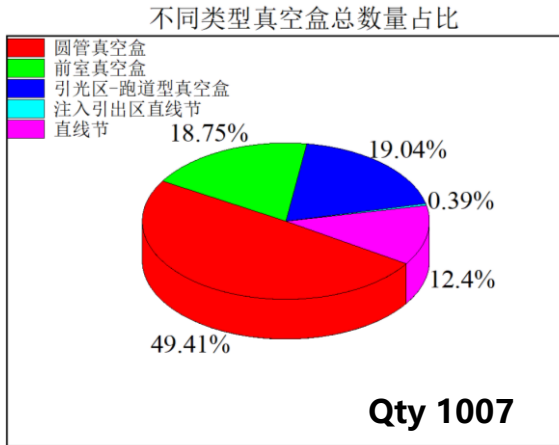




# NEG coating of vacuum chamber

Yongsheng Ma, Fei Sun, Tao Huang

- ◆ There are 1007 and the total length of 1239m vacuum chambers will be NEG coating, include 22mm round chambers, Antechambers and racetrack.





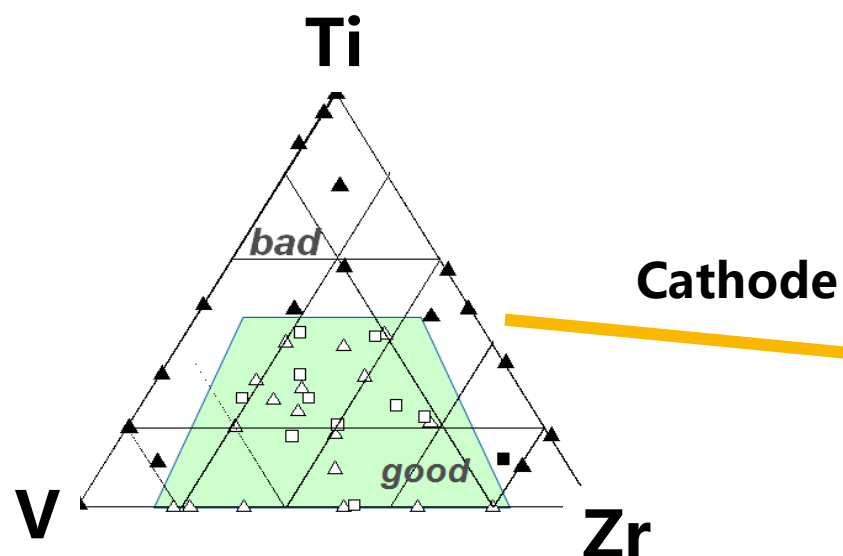
# Specification of NEG coating

Yongsheng Ma, Fei Sun, Tao Huang

## ◆ Specification of NEG coating

| Specification                                       | Design value             | attained                 |
|---|--------------------------|--------------------------|
| Pumping speed of H <sub>2</sub> L/s.cm <sup>2</sup> | 0.5                      | 0.72                     |
| Activation temperature °C                           | ≤180                     | 160                      |
| Capacity of CO mbar·L/s.cm <sup>2</sup>             | >1.0 × 10 <sup>-5</sup>  | 1.8 × 10 <sup>-5</sup>   |
| Thermal degassing Torr·L/s/cm <sup>2</sup>          | ≤2.5 × 10 <sup>-12</sup> | ≤2.5 × 10 <sup>-13</sup> |

|    |                                 |                                 |    |
|----|---------------------------------|---------------------------------|----|
| 3  | IVB                             | VB                              | V  |
| 3  | 4                               | 5                               |    |
| Sc | 22 Ti                           | 23 V                            | 24 |
|    | 钛                               | 钒                               |    |
|    | 3d <sup>2</sup> 4s <sup>2</sup> | 3d <sup>3</sup> 4s <sup>2</sup> |    |
| 6  | 47.87                           | 50.94                           | 52 |
| Y  | 40 Zr                           | 41 Nb                           | 42 |
|    | 锆                               | 铌                               |    |
|    | 4d <sup>2</sup> 5s <sup>2</sup> | 4d <sup>4</sup> 5s <sup>1</sup> |    |
| 1  | 91.22                           | 92.91                           | 95 |
| Lu | 72 Hf                           | 73 Ta                           | 74 |
|    | 铪                               | 钽                               |    |
|    | 5d <sup>2</sup> 6s <sup>2</sup> | 5d <sup>3</sup> 6s <sup>2</sup> |    |
| 系  | 178.5                           | 180.9                           | 18 |

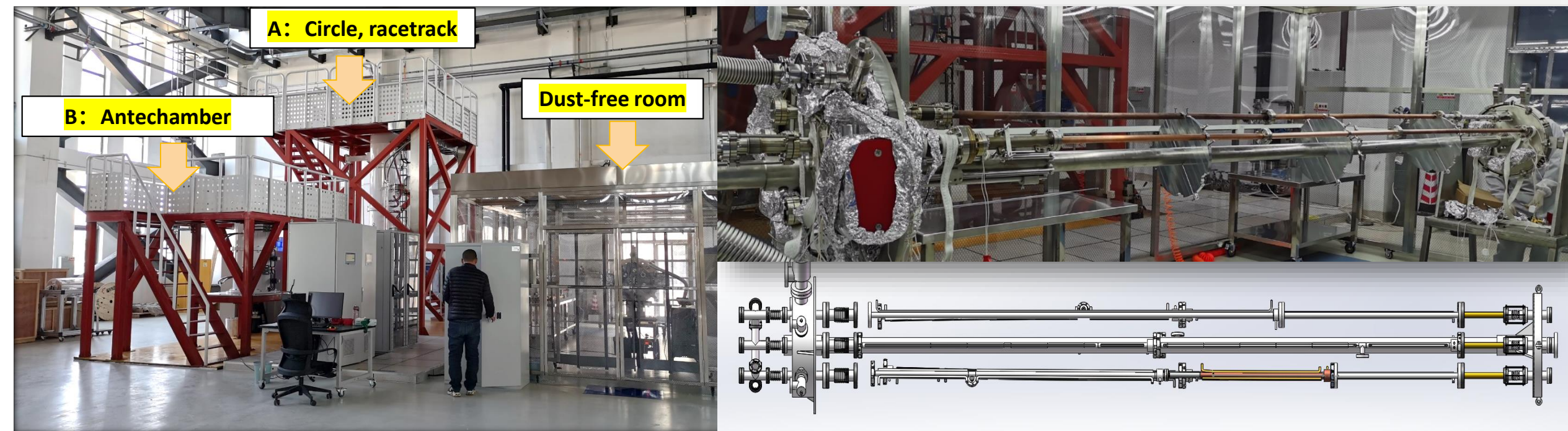




# Massive NEG coating

Yongsheng Ma, Fei Sun, Tao Huang

- The coating device A: Vacuum chambers are connected in parallel to 6 groups, each group of vacuum chambers length should be lower than 3.5m, outer diameter is about 0.47m;
- The coating device B: Antechamber are connected in parallel to 4 groups, each group of vacuum chambers length should be lower than 1.5m, due to its discharge difficulty.
- Two setups of NEG coating have been built for vacuum pipes of HEPS at IHEP Lab. And a lot of test vacuum pipes have been coated, which shows that NEG film has good adhesion and thickness distribution.

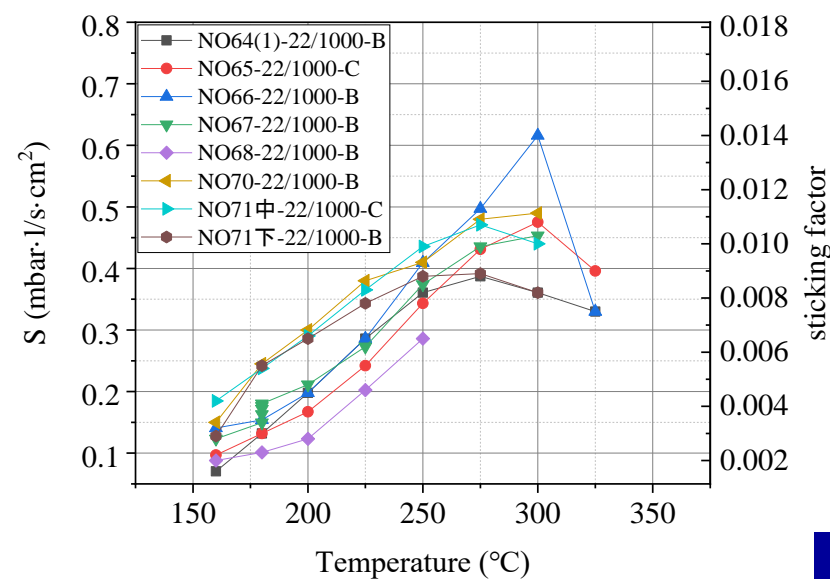
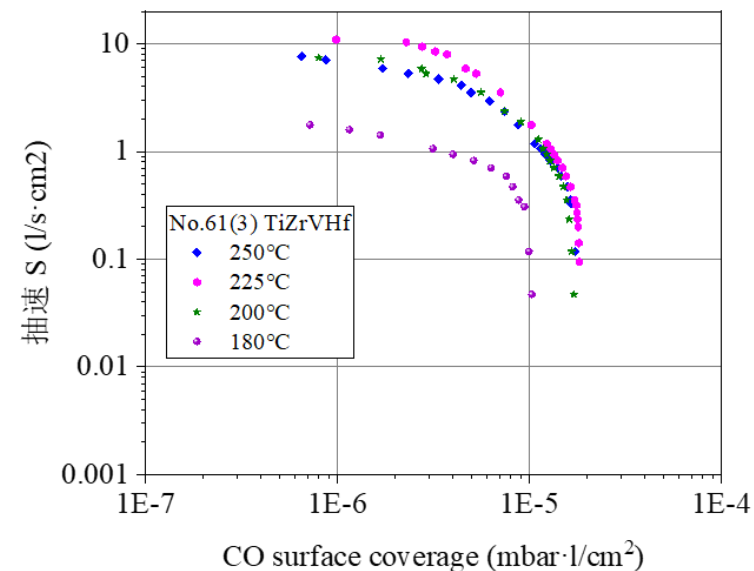
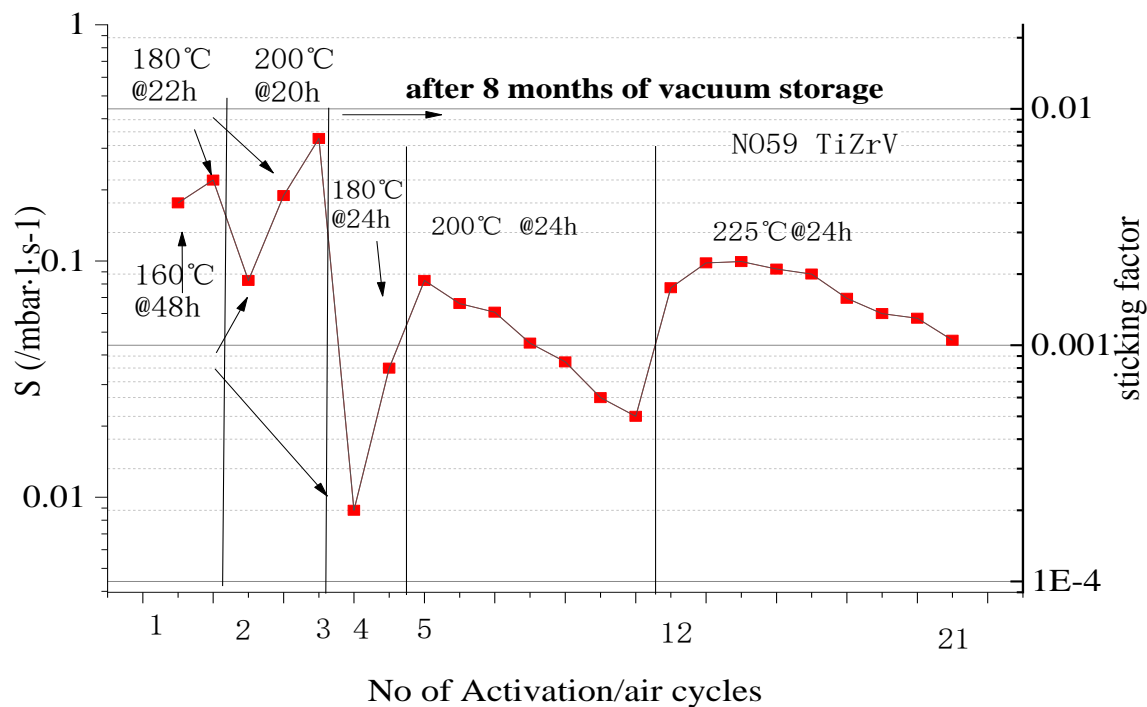


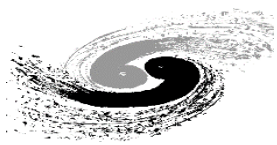


# Results of massive NEG coating

Yongsheng Ma, Fei Sun, Tao Huang

- ◆ The discharge of antechamber is very difficult due to its height is only 7mm , the whole antechamber which length is 1200mm has been NEG coated by last year.
- ◆ The life times of NEG coating activation exceeded 21@225°C.
- ◆ The stability of massive NEG coating is very important due to time limit for storage ring installation.

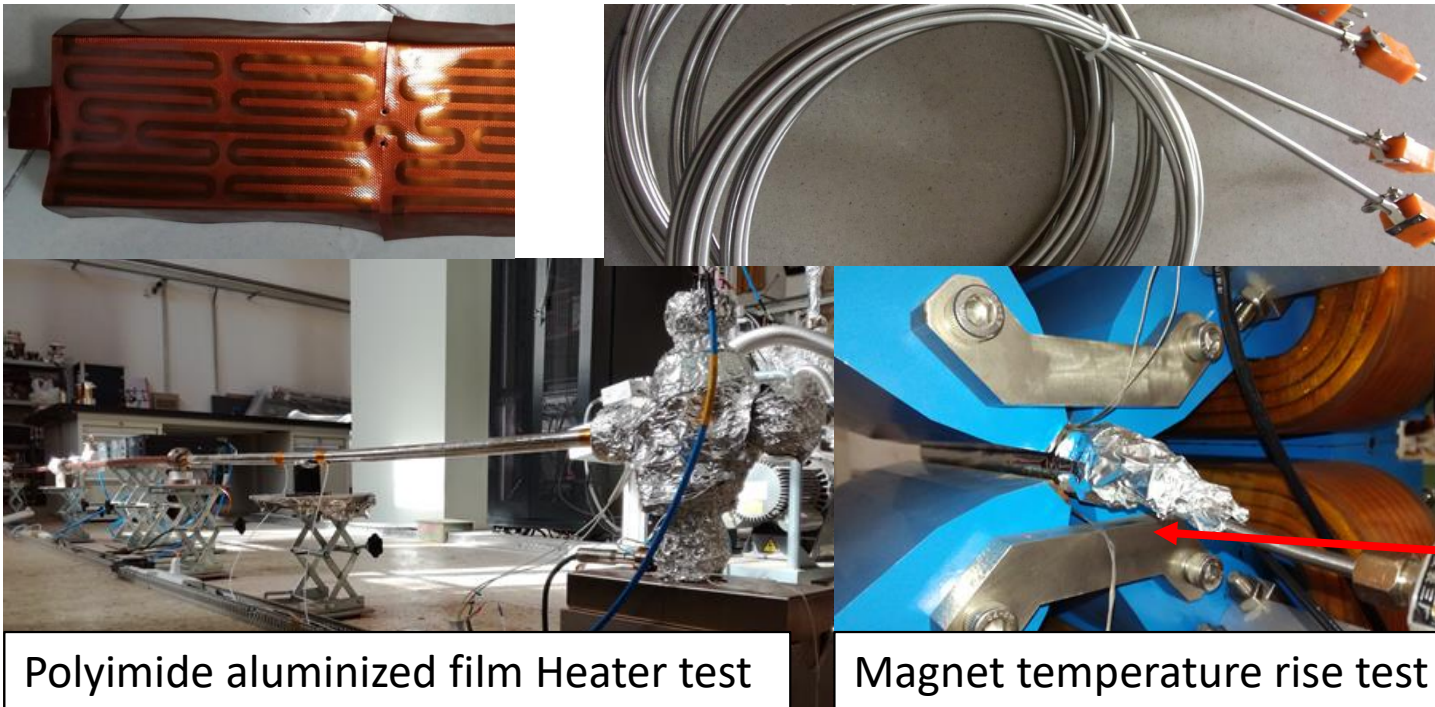
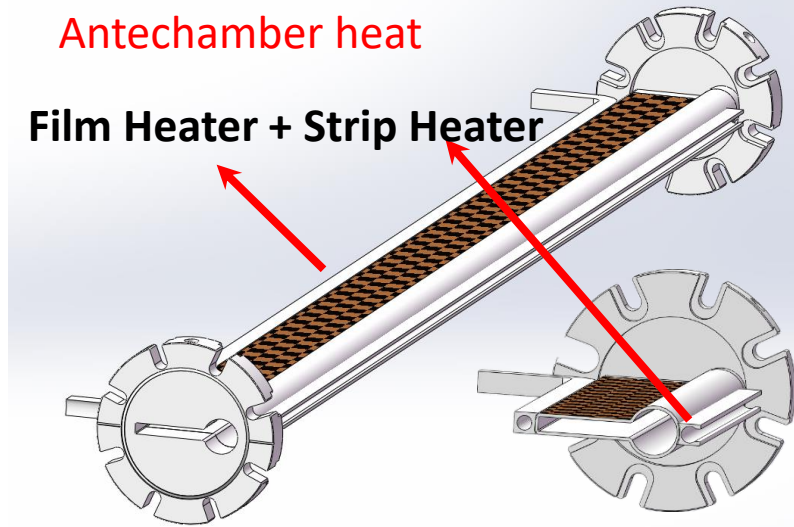




# 4 Bakeout experiments for NEG film activation

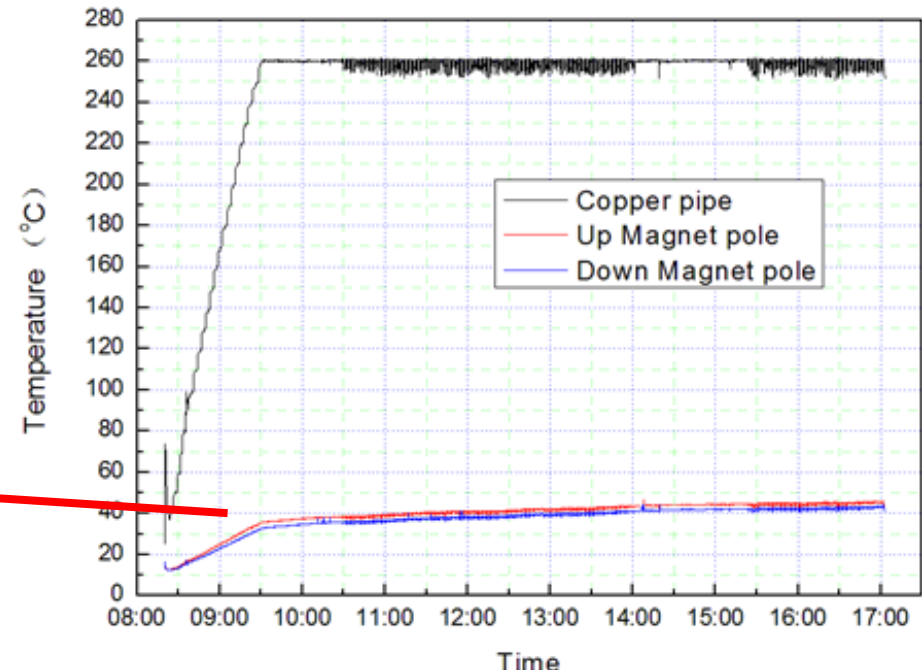
Baiqi Liu

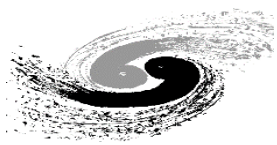
- Polyimide aluminized film Heaters (260°C) with a thickness of about 0.4mm were tested.
- For 260 °C baking temperature, if the gap between vacuum chamber and magnet pole increase from 0.5mm to 1mm, the rising temperature could reduce from 36.6 °C to 17.5 °C.
- Strip Heater will be employed in most vacuum chamber heating, due to its easier to be installation and reliability. The temperature variation is 30°C.



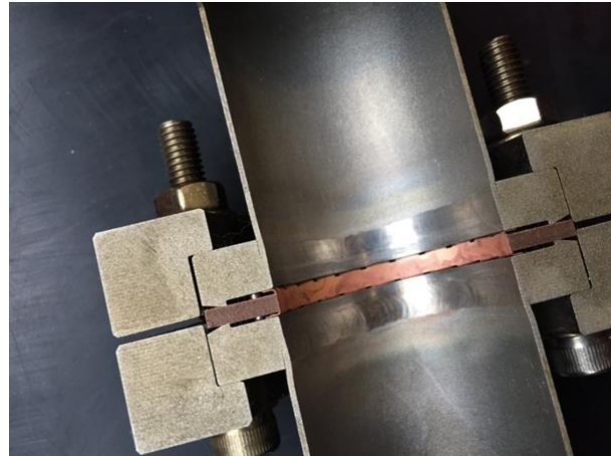
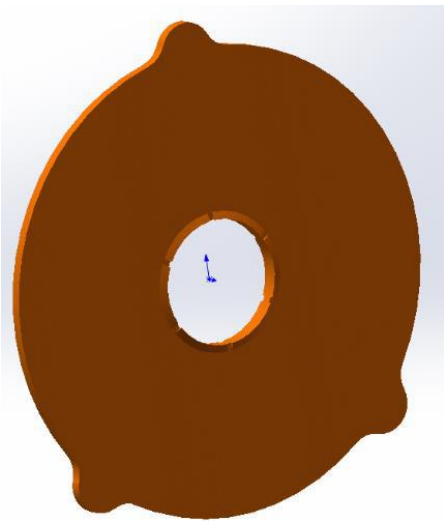
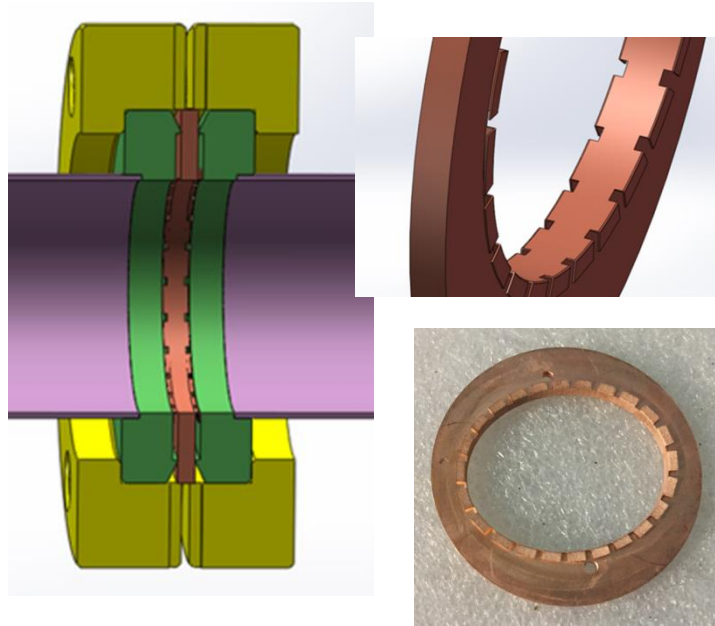
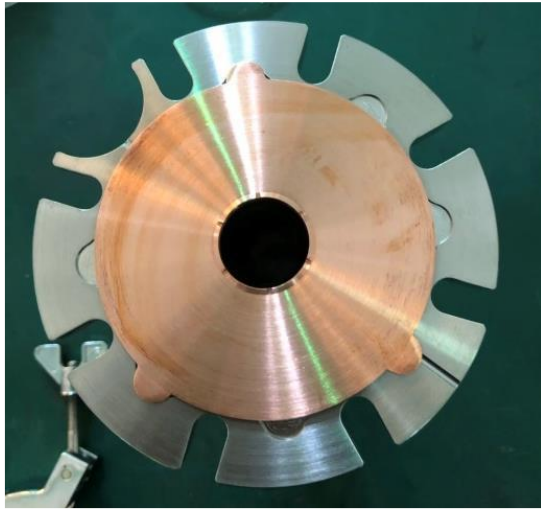
Polyimide aluminized film Heater test

Magnet temperature rise test

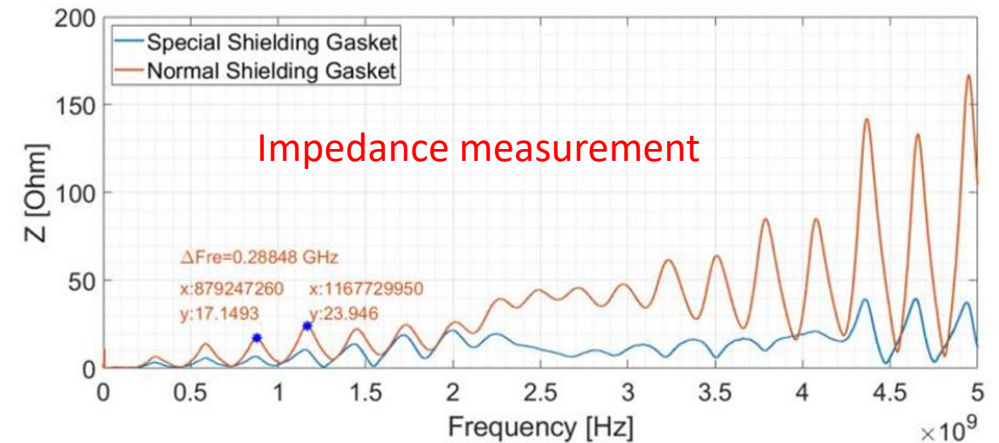




# Tests of low impedance gaskets



|                           |         |
|---------------------------|---------|
| Preload force /N          | 4       |
| Leakage rate/mbar.L/s     | < 1E-10 |
| Baking temperature/°C     | 250     |
| Baking time/h             | 24      |
| Repeated Baking times     | 6       |
| Repeat installation times | 4       |



Several experiments indicate the contact fingers have a good contact with flange surface.

Copper gasket with contact fingers



## 8. Summary

- The installation of all devices of Linac has been finished by July 2022, the static pressure has reached its design specifications.
- The membrane Ti windows have been applied in the dumps of linac.
- The installation and leak detection of the booster vacuum system have been completed and will be pumped down.
- Mass production of key equipment of storage ring will be soon finished.
- The vacuum chambers with the amount of 1007 and the total length of 1239m will be NEG-coated, which include the circle chambers of 22mm in diameter, Antechambers with a slit height of 7mm and racetrack chambers, many works need to be done.
- The installation of the storage ring devices began on 1th Feb 2023, it will take about one year to be finished.